



**Rui Amendoeira Esteves**

Master of Science

## **Python-based MEMS inertial sensors design, simulation and optimization**

Dissertation submitted in partial fulfillment  
of the requirements for the degree of

Master of Science in  
**Micro and Nanotechnologies Engineering**

Adviser: Michael Kraft, Full Professor, KU Leuven

Co-adviser: Joana Vaz Pinto, Invited Assistant Professor,  
NOVA University of Lisbon

Examination Committee

Chair: Prof. Dr. Hugo Manuel Brito Águas  
Rapporteur: Prof. Dr. Manuel João de Moura Dias Mendes  
Member: Prof. Dr. Michael Kraft



FACULDADE DE  
CIÊNCIAS E TECNOLOGIA  
UNIVERSIDADE NOVA DE LISBOA

**December, 2020**



## **Python-based MEMS design, simulation and optimization**

Copyright © Rui Amendoeira Esteves, NOVA School of Science and Technology, NOVA University Lisbon.

The NOVA School of Science and Technology and the NOVA University Lisbon have the right, perpetual and without geographical boundaries, to file and publish this dissertation through printed copies reproduced on paper or on digital form, or by any other means known or that may be invented, and to disseminate through scientific repositories and admit its copying and distribution for non-commercial, educational or research purposes, as long as credit is given to the author and editor.



*Scientia potentia est.*



## ACKNOWLEDGEMENTS

Obtaining a master degree is, so far, the greatest achievement in my life. So, I could not let this moment pass without acknowledging the people and institutions that supported me during these years and, in fact, made this possible.

The first acknowledgement must go to Professor Rodrigo Martins and Professor Elvira Fortunato for creating a truly pioneer degree in Portuguese science, effectively establishing Portugal in the nanotechnology area, and allowing students to be a part of science's future.

I would like to express my gratitude towards my adviser Professor Michael Kraft for taking me aboard the MNS team, allowing me to do research on a topic of significant interest, and providing a very positive work experience and environment. I would also like to thank Professor Joana Pinto for always being available and for the guidance, which was of great help in the writing of this work.

To Chen Wang, for all the hours, great guidance and friendship during my time in Leuven. To Mathieu and Sina, for all the precious advice and fun at the office. To the rest of the MNS team, for the warm reception, and for the excellent work environment you created.

Furthermore, I would like to thank all my colleagues that shared these five years with me. A special acknowledgement to Bernardo Madeira, Diogo Carvalho and José Barnabé - our time in Segundo Esquerdo was one of the best things I take from these years. Sharing this experience with you was a pleasure, and I will always be grateful for it.

To Eduardo Oliveira, who didn't live in the house, but was an essential part of it and a great friend. To Gui, Dmytro, Mariana Tomé, Raquel, Mariana Abreu, Maria Francisca, Guida, Alentejano, Diogo Lopes, Eduardo Encarnação and André Alves, for all the memories and help. To Pipa and Miguel, for all the advice, dinners, and very important guidance.

I want to thank my friends Madeira, Ticas, Zé Diogo, Diogo, Esha, Chico, Cacelas, Honório, Sousa, Ospital, Crua, Cunha, Tiago, and Manel. We have been together since elementary school, and the influence you have had in my life has been so significant and overwhelmingly positive that it is impossible to express

---

by words. Thank you for all the support and countless memories, I could not be more proud and grateful to call you friends.

I would like to express my enormous gratitude to my family. To my mother and father, for all the love, for always being present, for supporting me in every way, for always believing in me, and for always putting us first - you will always be an example to me. Thank you for all your sacrifices and efforts to provide for me. To my sister, for always being ready to defend your beliefs and to think for yourself, thus forcing me to be in touch with different points of view. Aos meus avós, pelo vosso amor e tempo. Pela inexplicável dedicação e devoção para com os filhos e netos, por tudo o que me ensinaram e deram até hoje - o meu muito obrigado, que nunca será suficiente. All of you (and Rocky) contributed to create the best family environment I could ever wish for, thank you.

Lastly, I want to express my deepest gratitude towards my girlfriend Maria. Having you in my life has been the greatest gift I have ever got, and I am nothing but thankful for having you as a colleague, friend and girlfriend. Thank you for always keeping me in the right track, for always believing in me, and for facing this Belgian adventure with me.



## ABSTRACT

---

With the rapid growth in microsensor technology, a never-ending range of possible applications emerged. The developments in fabrication techniques gave room to the creation of numerous new products that significantly improve human life. However, the evolution in the design, simulation, and optimization process of these devices did not observe a similar rapid growth. Thus, the microsensor technology would benefit from significant improvements in this domain.

This work presents a novel methodology for electro-mechanical co optimization of microelectromechanical systems (MEMS) inertial sensors. The developed software tool comprises geometry design, finite element method (FEM) analysis, damping calculation, electronic domain simulation, and a genetic algorithm (GA) optimization process. It allows for a facilitated system-level MEMS design flow, in which electrical and mechanical domains communicate with each other to achieve an optimized system performance. To demonstrate the efficacy of the co-optimization methodology, an open-loop capacitive MEMS accelerometer and an open-loop Coriolis vibratory MEMS gyroscope were simulated and optimized - these devices saw a sensitivity improvement of 193.77% and 420.9%, respectively, in comparison to its original state.

**Keywords:** Microelectromechanical systems (MEMS), inertial sensors, Python, finite element method, genetic algorithm, optimization, accelerometer, gyroscope

---



## RESUMO

---

Com o rápido crescimento observado na tecnologia de micro sensores, emergiu um vasto numero de aplicações possíveis. Os desenvolvimentos que ocorreram nas técnicas de micro e nano fabricação deram lugar à criação de um grande número de novos produtos que melhoram significativamente a vida humana. No entanto, a evolução no processo de design, simulação e optimização destes dispositivos não acompanhou o progresso previamente mencionado. A tecnologia dos micro sensores beneficiaria, então, de um desenvolvimento significativo neste domínio.

Este estudo apresenta uma nova metodologia para a co-optimização electro-mecânica de microssistemas electromecânicos (MEMS) para sensores de inércia. O software desenvolvido é composto por um bloco para design de geometria, outro bloco para análise com método de elementos finitos (FEM), um *script* de cálculo de amortecimento, uma simulação da interface electrónico e um processo de optimização pelo algoritmo genético (GA). Esta ferramenta permite um processo de design de MEMS facilitado, no qual os domínios electrónico e mecânico comunicam entre si para atingir um sistema final optimizado. Para demonstrar a eficácia da metodologia de co-optimizacao, um acelerómetro capacitivo MEMS e um giroscópio vibratório de Coriolis MEMS foram simulados e optimizados - estes dispositivos viram a sua sensibilidade aumentada em 193.77% e 420.9%, respectivamente, em relação ao seu estado original.

**Palavras-chave:** Microssistemas electromecânicos (MEMS), sensores de inércia, Python, método dos elementos finitos, algoritmo genético, optimização, acelerómetro, giroscópio

---



# CONTENTS

<b>List of Figures</b>	<b>xv</b>
<b>List of Tables</b>	<b>xvii</b>
<b>Acronyms</b>	<b>xix</b>
<b>Symbols</b>	<b>xxi</b>
<b>1 Motivation and objectives</b>	<b>1</b>
<b>2 Work strategy</b>	<b>3</b>
<b>3 Introduction</b>	<b>5</b>
3.1 MEMS inertial sensors . . . . .	5
3.1.1 Accelerometers . . . . .	6
3.1.2 Gyroscopes . . . . .	7
3.2 Genetic Algorithm . . . . .	8
3.3 MEMS design, simulation and optimization . . . . .	8
<b>4 Simulation Methodology</b>	<b>11</b>
4.1 Finite Element Method . . . . .	11
4.2 Python language and libraries . . . . .	12
<b>5 Results and discussion</b>	<b>13</b>
5.1 Python simulation and optimization software . . . . .	13
5.1.1 MEMS geometry design in Python . . . . .	13
5.1.2 FEM simulation for displacement and modal analysis . . . .	14
5.1.3 Electronic domain simulation . . . . .	16
5.1.4 Damping calculation . . . . .	19
5.1.5 Genetic algorithm optimization . . . . .	21
5.2 Case study 1: MEMS capacitive accelerometer . . . . .	22
5.2.1 Design analysis . . . . .	22

## CONTENTS

---

5.2.2 Optimization results . . . . .	23
5.3 Case study 2: linear MEMS vibratory gyroscope . . . . .	26
5.3.1 Design analysis . . . . .	27
5.3.2 Optimization results . . . . .	28
<b>6 Conclusion and Future Perspectives</b>	<b>33</b>
<b>Bibliography</b>	<b>35</b>
<b>Annexes</b>	<b>43</b>
<b>I Software implementation on MEMS accelerometer</b>	<b>43</b>
<b>II Software implementation on MEMS gyroscope</b>	<b>57</b>
<b>III Permittivity values</b>	<b>97</b>

## LIST OF FIGURES

3.1	Lumped model of accelerometer attached to a body . . . . .	6
3.2	Working principle of MEMS coriolis vibratory gyroscope . . . . .	7
3.3	General MEMS design, simulation and optimization process-flow . . .	8
4.1	The finite element method approach . . . . .	11
5.1	General block diagram for the developed software. . . . .	13
5.2	Capacitive sensing structures present in both case studies . . . . .	17
5.3	Electrostatic actuation system present in MEMS gyroscope (case study 2) . . . . .	18
5.4	Block diagram of capacitance to voltage converter circuit implemented with both MEMS devices . . . . .	19
5.5	Viscous damping effects modelled in the software . . . . .	20
5.6	Workflow of the programmed genetic algorithm . . . . .	21
5.7	Mass-spring-damper model . . . . .	22
5.8	MEMS capacitive accelerometer design . . . . .	23
5.9	MEMS accelerometer mode shape corresponding to the natural fre- quency of 3284 Hz . . . . .	23
5.10	Capacitive MEMS accelerometer system-level model. . . . .	24
5.11	Mesh convergence study for MEMS accelerometer . . . . .	24
5.12	Evolution of the MEMS accelerometer through the six generations of the GA, the suspension beam width is reduced and the proof mass is enlarged . . . . .	26
5.13	Mass-spring-damper model of MEMS gyroscope design . . . . .	26
5.14	Linear vibratory MEMS gyroscope design [7] . . . . .	27
5.15	Linear vibratory MEMS gyroscope system-level model. . . . .	28
5.16	Mesh convergence study for MEMS gyroscope . . . . .	29
5.17	Evolution of the MEMS gyroscope through the six generations of the GA - the proof-mass became larger; the u-beams, the sense comb fin- gers, and the proof-mass frame became thinner . . . . .	30

LIST OF FIGURES

---

5.18 Frequency modes of original and optimized MEMS gyroscope, the  
movement modes became more pronounced . . . . . 31



## LIST OF TABLES

5.1	Material properties of Silicon crystal (100) [53] . . . . .	16
5.2	Initial geometric parameters of MEMS accelerometer . . . . .	23
5.3	Geometric and performance parameters of original and final accelerometer . . . . .	25
5.4	Initial geometric parameters of MEMS gyroscope . . . . .	27
5.5	Geometric and performance parameters of original and optimized gyroscope . . . . .	30
III.1	Permittivity values . . . . .	97



## ACRONYMS

CAD	computer-assisted design
DoF	degree of freedom
FEA	finite element analysis
FEM	finite element method
FOM	figure of merit
GA	genetic algorithm
GPS	global positioning system
MEMS	microelectromechanical system
PDEs	partial differential equations
VDC	vehicle dynamic control



## SYMBOLS

$V_{AC}$	alternate-current voltage
$P_a$	ambient pressure
$A$	area
$V_{C2V}$	voltage from the conversion of capacitance
$C_{bottom}$	capacitance between the bottom electrode and the proof-mass
$C_{top}$	capacitance between the top electrode and the proof-mass
$C_{int}$	reference capacitance
$c_{squeeze}$	squeeze damping coefficient
$c_{slide}$	slide damping coefficient
$m_m$	mass of the moving structure
:	colon operator
$m_C$	mass subjected to Coriolis force
$\Delta C_s$	capacitance variation from the sensor
$F_c$	damping force
$V_{DC}$	direct-current voltage
$\{U\}$	displacement function
$disp$	displacement
$u$	displacement vector field
$d$	distance between electrodes
$x_0$	drive amplitude
$\omega_D$	drive mode frequency
$\omega_S$	sense mode frequency
$\mu_{eff_{squeeze}}$	effective viscosity for squeeze film damping
$\mu_{eff_{slide}}$	effective viscosity for slide film damping
$F_{balanced}$	electrostatic force from balanced actuation
$F_{comb}$	electrostatic force from comb fingers

## SYMBOLS

---

$\lambda$	eigenvalue
$\omega$	eigenfrequency
$\epsilon_0$	free space permittivity
$\epsilon$	symmetric strain-rate tensor
$\epsilon_r$	relative permittivity of the dielectric medium
$f$	body force per unit of volume
$I$	identity tensor
$K_n$	Knudsen number
$\lambda_L$	Lamé parameter $\lambda$
$L$	length of the comb fingers
$[M]$	mass matrix
$y_0$	mechanical scale factor
$\lambda_f$	mean free path
$\Delta f$	frequency mismatch
$\mu_L$	Lamé parameter $\mu$
$\mu$	mean viscosity of the medium
$n$	outward pointing unit normal at the boundary
$\nabla$	divergence operator
$N$	number of comb fingers
$\Omega$	body domain
$\Omega_Z$	angular-rate around the z-axis
$a$	overlapping area between electrodes and proof-mass
$c$	ratio between the width and length
$Q_{factor}$	quality factor
$m_S$	moving mass in the sense mode
$Q_{sense}$	quality factor of sense mode
$\sigma$	stress tensor

$\sigma_s$	squeeze number
$[K]$	stiffness matrix
$t$	thickness
$tr$	trace operator
$v$	test function
$\hat{V}$	vector-valued test function space
$V_{cm}$	reference voltage
$V_{DD}$	supply voltage
$V$	voltage





## MOTIVATION AND OBJECTIVES

In the past decade, inertial sensor technology has suffered a rapid market growth: smartphones and tablets, gaming systems, virtual reality equipment, toys, and power tools are good examples of the wide adoption these devices have seen on consumer electronics products [1]. Most people already carry a [microelectromechanical system \(MEMS\)](#) inertial sensor in their pockets - the ordinary smartphone combines gyroscopes and accelerometers in order to provide the user with a [global positioning system \(GPS\)](#), a rotation detector and velocity measurements.

However, these mundane implementations are not alone in the inertial sensor world - the automotive [2], aerospace [3], and military industry make use of these devices in numerous applications. Apart from the standard GPS, modern vehicles now possess a [vehicle dynamic control \(VDC\)](#) system that helps the automobiles with regaining control in the event of skidding [4]. In the military industry there are ongoing efforts to integrate MEMS inertial sensors with projectiles and aircraft, providing a chance to measure in-flight dynamics [5].

In order to design, simulate, and optimize these devices, engineers have divided the process into two very distinct - yet symbiotic - domains: mechanical and electrical. This workflow is often severely divided, and usually a great deal of simplification is applied to one of the domains in order to achieve a complete simulation and optimization of the other one [6]. Moreover, the typical design methodology combines multiphysics software and a programming language interpreter program. The fact that there is a very restricted set of tools to choose from, combined with the need for compatibility between different commercial software, dramatically limits the potential for customization and adaptation to specific designs.

This work aims to develop a novel co-simulation and co-optimization process for MEMS devices fully based on Python, in order to provide a complete open-source solution that provides an insight into both the mechanical and the electrical domains, while paying attention to their interaction.



## WORK STRATEGY

This work followed three consecutive phases:

1. The initial step was to develop the Python program. Initially, research was conducted to find similar work as well as to search for software libraries that could be of use in this endeavour. Then, a geometry builder part, a [finite element method \(FEM\)](#) block, and an electrical script were built. Finally, a [genetic algorithm \(GA\)](#) was designed and connected to the program. The four sections assemble a complete general-purpose MEMS simulation and optimization software.
2. The second step encompassed designing, simulating, and optimizing a capacitive MEMS accelerometer with the new program. The simulations are compared with commercial multiphysics software, and the optimization result is analyzed. This step represents the program's first implementation on a MEMS inertial sensor.
3. The third step was to test the software with a MEMS gyroscope. This design represented a remarkable challenge for the program to process, simulate and optimize - thus, making for a reliable way to validate further the system when applied to inertial sensors.



## INTRODUCTION

Microelectromechanical Systems (MEMS) are defined as a combination of electrical and mechanical systems at micrometer scale. These devices are fabricated using photolithography methods. This technology allows for the fabrication of moving microstructures on a substrate, allowing for the creation of remarkably complex structures which turn into mechanical and electrical systems [7].

### 3.1 MEMS inertial sensors

MEMS inertial sensors are a group of sensors that measure acceleration or angular motion - the first is referred to as accelerometer and the second as gyroscope. With the advent of the micromachining technology [8], the production costs for these devices decreased enough to oversee their expansion into consumer applications. Previously confined to cost-heavy industries, such as military and aerospace, inertial sensors rapidly grew into many other areas such as automotive, biomedical, navigation, and smart systems [9].

One of the most prominent applications for micromachined accelerometers is in the automotive industry [10]. A study on the perspectives of MEMS sensors by Senturia *et al.* [11] stated that the silicon accelerometer dominates the market for automotive airbag deployment, a life-saving mechanism responsible for avoiding 2790 deaths per year in the United States of America alone [12]. MEMS accelerometers applications in this area include crash and skid detection - both crucial when designing stabilization systems [13].

In the biomedical industry, there is a growing interest in the integration of MEMS accelerometers into various applications. Kusmakar *et al.* [14] demonstrated the potential to build an ambulatory monitoring convulsive seizure detection system, using an accelerometer. Fall detection systems using MEMS accelerometers are being widely adopted [15, 16]. Van Thanh *et al.* [17] developed a prototype for fall detection that alerts an emergency contact in case the elderly person has an accident. Furthermore, fitness trackers comprising MEMS accelerometers are now popularly used by the general public [18].

Similarly, micromachined gyroscopes are widely adopted in the automotive industry [2] - seeing applications in rollover protection, stability and active control systems, and inertial navigation. A gyroscope detects the angular rate of a car, and if this value hits a critical threshold - a safety system will adjust the steering wheel and brakes to prevent the vehicle from overturning [9]. Another common application for MEMS gyroscopes is platform stabilization - using these sensors to detect an angular motion and automatically adjust a platform such as a video camera or robotic arm, to achieve a stable surface [19].

Inertial sensors have a bright future ahead of them with an endless array of possibilities. Thus, it is of the most significant interest to research and develop new ways of designing, simulating and optimizing MEMS inertial sensors. Novel methodologies of co-simulation can open doors to news designs and applications, as well as creating a more efficient work-flow.

### 3.1.1 Accelerometers

An accelerometer is a sensor which can detect acceleration. The general working principle of this device is described as a body which suffers a detectable displacement when it is under an external acceleration force. Despite the large number of accelerometers types, the vast majority has a proof-mass attached to a reference frame by a suspension system, illustrated in Figure 3.1 - this mechanical structure is designed to move along a specific axis, in order to detect acceleration in this direction [9].

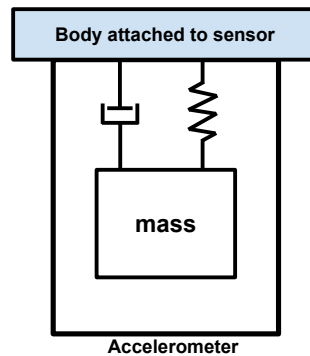


Figure 3.1: Lumped model of accelerometer attached to a body

The deflections are transformed into an electrical signal. This process of transducing can take three forms: resistive interfaces, piezoelectric interfaces, and capacitive interfaces [20]. In this work, the studied inertial sensors have a capacitive transducing interface - these devices comprise a set of one or more fixed

electrodes and one or more moving electrode. The movement caused by an acceleration modifies the distance between electrodes, provoking a capacitance change which is then captured by a readout circuit.

### 3.1.2 Gyroscopes

A gyroscope is a sensor that measures the angular rate of an object - the rate of rotation. There are three types of gyroscopes: spinning mass, optical, and vibrating gyroscopes [21]. For micromachined gyroscopes, the most common approach to sense an angular rate is to use vibrating mechanical elements. This type of devices involve no rotating parts which endure friction and wear, allowing for a successful miniaturization under micromachining techniques. Vibrating gyroscopes induce and detect Coriolis force in order to measure the angular motion [7].

The Coriolis force is a fictitious force that emerges from the Coriolis effect, which only acts on an object when the motion is observed from a rotating non-inertial reference frame. Jean Bernard Léon Foucault demonstrated this phenom in 1851, with the Foucault pendulum [22]: when a swinging pendulum attached to a rotating platform is observed by a stationary observer from above - the pendulum oscillates along a straight line; however, an observer in the rotating platform would see that the line precesses. That precession can only be described with dynamic equations if the Coriolis force is included [7, 23].

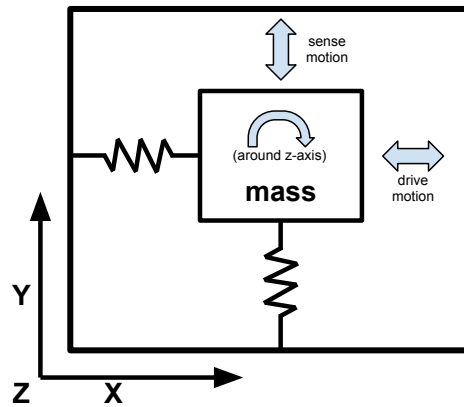


Figure 3.2: Working principle of MEMS coriolis vibratory gyroscope

Coriolis vibratory gyroscopes comprise an inertial mass element and a suspension system that keep the proof-mass suspended above the substrate. The sensitive element is driven to oscillation along one axis with known amplitude (driving mode), when the device rotates around another axis, the Coriolis effect causes the proof-mass to move in an orthogonal direction (sensing mode). In this study, the displacement in the sense mode produces a detectable capacitance

change [24]. This working principle is illustrated in Figure 3.2, in which the gyroscope detects angular motion around the z-axis.

## 3.2 Genetic Algorithm

When Charles Darwin, in the nineteenth century, revolutionized science by discovering the processes by which nature selects and evolves its organisms [25], it was not possible to foresee the numerous applications his discoveries would inspire. In the same century, Gregor Mendel laid down the bases of genetic inheritance [26] - complementing Darwin's findings. The genetic algorithm was designed, taking the aforementioned principles as inspiration, making use of computational resources to optimize all kinds of devices and processes.

The genetic algorithm applies evolution principles to a set of individuals: the algorithm runs through several generations, starting from an initial population with initial parameters and defined fitness goals, and letting the best individuals survive and reproduce themselves - mixing the parameters of the ancestors with random mutations, imitating the natural process until the population converges to a higher performance state [27].

In this study, the genetic algorithm is applied to MEMS inertial sensors, setting electro-mechanical performance parameters as fitness goals in order to achieve a complete co-optimization.

## 3.3 MEMS design, simulation and optimization

The design, simulation, and optimization process of a MEMS device is illustrated in Figure 3.3, and can be broadly described by the sequence: design of initial geometry, mechanical parameter simulation and optimization, design of electrical interface, and simulation of complete system [28].

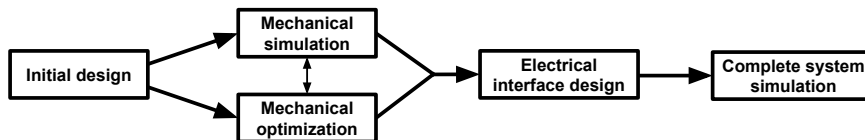


Figure 3.3: General MEMS design, simulation and optimization process-flow

In order to design, simulate and optimize MEMS inertial sensors, engineers have separated the process into two very distinct - yet symbiotic - domains: mechanical and electrical. This workflow is often severely divided, and usually, a



great deal of simplification is applied to one of the domains to achieve a complete simulation and optimization of the other.

MEMS mechanical structures are usually designed in a [computer-assisted design \(CAD\)](#) software and commonly comprise thousands of [degree of freedom \(DoF\)](#) which lead to a high computational cost when simulating mechanical behaviour. To bypass this obstacle, engineers have used reduced-order modelling methods to build system-level models [29], bringing the thousands of DoF down to a few, with the three DoF being the most basic option, frequently used when designing closed-loop control systems. For example, Hung *et al.* [30] used low-order models to improve simulation time significantly, while Kudryatsev *et al.* [31] tried to achieve a reduced-order model for a MEMS piezoelectric energy harvester, and Nayfeh *et al.* [32] developed two reduced-order models for MEMS applications.

The aforementioned method can be helpful when designing and optimizing the sensor's electrical interface; however, it fails to take into consideration the full complex mechanical structure, and consequently, the interaction between electrical and mechanical domains.

Moreover, the typical optimization methodology combines multiphysics software and a programming language interpreter program. Wang *et al.* [33] presented a MEMS mechanical optimization method that allows for the generation of freeform geometries - combining COMSOL [34] finite element analysis and modelling with a [GA](#) implemented in MATLAB [35], demonstrating its effectiveness with the optimization of a MEMS accelerometer. Solouk *et al.* [36] used the same methodology to optimize a MEMS gyroscope concerning an automotive application.

Although this approach takes into consideration the complex mechanical structure of MEMS as well as its electrical interface, it does possess several limitations. It does not fully capture the interaction between mechanical and electrical domains, and the fact that there is a very restricted set of tools to choose from, combined with the need for compatibility between different commercial software ends up limiting the potential for customization and adaptation to specific designs.



## SIMULATION METHODOLOGY

### 4.1 Finite Element Method

In this work, the [finite element method \(FEM\)](#) is implemented in the developed software, as it is a fundamental mathematical tool to simulate mechanical structures. It is chosen over the finite difference method due to its ability to handle complex geometries. It is also used by COMSOL [34], a simulation multiphysics software employed to provide a viable comparison and validation means.

The finite element method approaches any problem by subdividing a continuous entity into finite smaller parts, solve each one individually, and reassemble them as seen on Figure 4.1. It is a mathematical tool necessary to apply [finite element analysis \(FEA\)](#) to a physical phenom. Using numerical methods to deeply comprehend any phenomena is essential, mostly because many of the physical processes, and indeed the vast majority of solid mechanics ones, are described by [partial differential equations \(PDEs\)](#) [37].

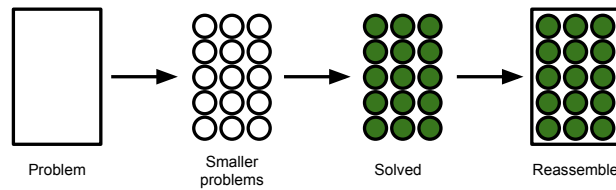


Figure 4.1: The finite element method approach

For a computer to solve PDEs, it applies the FEM to divide an extensive system into smaller subparts - finite elements. This division is called space discretization, and the generation of a mesh achieves it - this is a way of transcribing a 2D or 3D object into a series of mathematical points that can be analyzed.

There are several categories of PDEs: elliptic, hyperbolic, and parabolic [38]. This study focuses on solid mechanics simulation, thus, the main category applied to this area is elliptic, which can be solved using a variational method - FEM.

A variational method has its basis on the principle of energy minimization: when a boundary condition (e.g. displacement) is applied, the configuration where the total energy is minimum is the one that prevails. The process of solving

these equations with this method starts with multiplying the PDEs by a test function, then integrate the resulting equation over the domain, and finally perform integration by parts with second-order derivatives. The unknown function to be approximated is named trial function. The trial and test functions belong to a particular function space, which specifies the functions properties as well as the spatial domain in which they act [39].

## 4.2 Python language and libraries

The Python [40] programming language was used to develop the co-simulation and co-optimization system in this study. Python is a high-level language exceptionally well suited for scientific and engineering environments - its highly modular nature and clean syntax provide a simple and direct code writing suitable in many scientific applications [41].

The language's open source license allows the user to use, sell, and distribute any developed Python-based application with no need for special permissions. Its ability to interact with a wide range of other software, to run on a significant number of platforms, to allow realtime code development without the need to compile every time it changes, makes the language a powerful candidate for scientific computing and application development [42].

The advantages mentioned above contribute heavily to the selection of Python for this work. However, the main reason for this choice lies in the countless number of library modules provided either officially from Python or from the global developer's community, which opens the door to a never-ending number of possible combinations and applications. A software was developed in Python to simulate and optimize MEMS devices. It used different modules and libraries like *pygmsh*, *meshio*, and *FEniCS* to generate and simulate 3D geometries.

The *pygmsh* [43] module was used to build the desired geometries. It combines *Gmsh* [44], a finite element mesh generator and Python to create a versatile tool which can create complex geometries with code. The *meshio* [45] module was implemented on the software in order to perform mesh import and export operations. It is useful to allow information processing between the various program parts and provides the possibility to visualize generated meshes.

The *FEniCS* [46] library is a powerful open-source computing platform for PDEs. It enables users to translate scientific models into efficient finite element code [47] and supports parallel processing - which allows for a significant computation speed increase. The software used this module to perform FEM simulation.

## RESULTS AND DISCUSSION

### 5.1 Python simulation and optimization software

A complete MEMS co-simulation and co-optimization program comprises different essential blocks. As introduced in Chapter 2, this type of software needs to englobe:

1. A geometry designer or processor with meshing abilities.
2. A FEM simulation block powerful enough to process different mesh sizes with varying degrees of complexity.
3. A personalized electrical domain script capable of interpreting the mechanical results for each MEMS device.
4. A GA section that takes into consideration both mechanical and electrical performance parameters.

A software covering all the aforementioned abilities was developed with a general structure depicted in Figure 5.1. This program also englobed a viscous damping calculation, which the genetic algorithm takes into consideration. In this way, the optimization considers an important parameter that is a direct result of the interaction between mechanical and electrical domains.

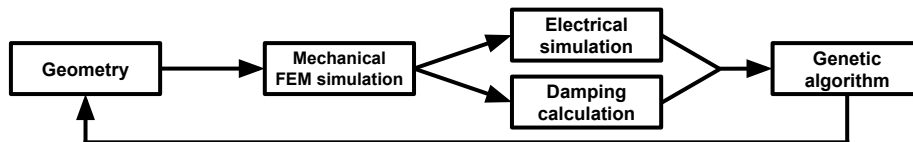


Figure 5.1: General block diagram for the developed software.

#### 5.1.1 MEMS geometry design in Python

A competent geometry design and meshing system requires several fundamental characteristics: the ability to create different shapes and perform boolean operations on them (union, difference, intersection, and complement), the capacity

to create a customizable mesh to be assigned to the created geometry, and the possibility to import and export files.

For this purpose, as previously mentioned in Chapter 4.2, two Python libraries were chosen - *pygmsh* and *meshio*. *Pygmsh* is used for geometry building and mesh generation, next the *meshio* library is applied to generate a file that can be read by the other software blocks. This implementation is shown in Listing I.1 and II.1.

### 5.1.2 FEM simulation for displacement and modal analysis

The FEM block is the most complex and vital simulation in the program, arguably the core of the software. In this study, as stated in Chapter 4.1, this tool is used to solve PDEs problems involving linear elasticity equations: the first is to calculate the displacement resulting from an applied force, and the second is to perform a modal analysis - obtaining the MEMS eigenfrequency modes.

#### 5.1.2.1 Displacement analysis

For MEMS inertial sensors simulation, PDEs modelling small deformations of elastic bodies become the main mechanical objects of study [20]. When a force is applied to a body  $\Omega$ , the equations describing the suffered deformations on isotropic elastic conditions are the following [48]:

$$-\nabla \cdot \sigma = f \text{ in } \Omega \quad (5.1)$$

$$\sigma = \lambda_L \text{tr}(\epsilon) I + 2\mu_L \epsilon \quad (5.2)$$

$$\epsilon = \frac{1}{2}(\nabla u + (\nabla u)^T) \quad (5.3)$$

In these equations:  $\nabla$  represents the divergence operator [49],  $\sigma$  is the stress tensor [50],  $f$  stands for the body force per unit of volume,  $\lambda_L$  and  $\mu_L$  denote the Lamé's elasticity parameters regarding the body's material [51],  $I$  signify the identity tensor,  $tr$  represents the trace operator (on a tensor),  $\epsilon$  stands for the symmetric strain-rate tensor, and  $u$  is the displacement vector field.

Combining (5.2) and (5.3) yields

$$\sigma = \lambda_L(\nabla \cdot u)I + \mu_L(\nabla u + (\nabla u)^T) \quad (5.4)$$

As referred in Section 4.1, the variational formulation of (5.1 - 5.3) begins with the inner product of equation (5.1) and a test function  $v \in \hat{V}$ , where  $\hat{V}$  stands for a vector-valued test function space, and integrating it over the domain  $\Omega$ .

$$-\int_{\Omega} (\nabla \cdot \sigma) \cdot v \, dx = \int_{\Omega} f \cdot v \, dx \quad (5.5)$$

The expression  $\nabla \cdot \sigma$  includes second-order derivatives that belong to the unknown  $u$ , so the term that contains it is integrated by parts.

$$-\int_{\Omega} (\nabla \cdot \sigma) \cdot v \, dx = \int_{\Omega} \sigma : \nabla v \, dx - \int_{\partial\Omega} (\sigma \cdot n) \cdot v \, ds \quad (5.6)$$

The colon operator represents the inner product of two tensors, and  $n$  is the outward pointing unit normal at the boundary. The expression  $\sigma \cdot n$  is known as the stress vector and regularly designates a boundary condition - it is assumed that it is prescribed on a part  $\partial\Omega_T$  of the boundary as  $\sigma \cdot n = T$ , where  $T$  is a constant. On the rest of the boundary, the value of the displacement is represented as a Dirichlet [52] condition. Thus, it is obtained:

$$\int_{\Omega} \sigma : \nabla v \, dx = \int_{\Omega} f \cdot v \, dx + \int_{\partial\Omega_T} T \cdot v \, ds \quad (5.7)$$

Replacing the stress tensor,  $\sigma$  from (5.4) in the previous equation (5.7) produces the variational form with  $u$  as unknown. It is now possible to summarize the variational formulation - find  $u \in V$  in a manner that

$$a(u, v) = L(v) \quad \forall v \in \hat{V} \quad (5.8)$$

In which

$$a(u, v) = \int_{\Omega} \sigma(u) : \nabla v \, dx \quad (5.9)$$

$$L(v) = \int_{\Omega} f \cdot v \, dx + \int_{\partial\Omega_T} T \cdot v \, ds \quad (5.10)$$

In the colon operator product  $\sigma : \nabla v$ , if  $\nabla v$  is represented as a sum of its symmetric and anti-symmetric parts, the remaining part will be the symmetric one because  $\sigma$  is a symmetric tensor. This allows for the replacement of  $\nabla v$  by the symmetric gradient  $\epsilon(v)$ :

$$a(u, v) = \int_{\Omega} \sigma(u) : \epsilon(v) \, dx \quad (5.11)$$

The equation 5.11 is the one that clearly emerges from the principle of energy minimization applied to potential elastic energy and it is the one implemented on the developed software, as seen on Listing I.2 and II.2. In this work, the MEMS designer inputs the required boundary conditions and the program takes into consideration those constants to evaluate aforementioned equation.

The software needs to possess the inertial sensor's material properties in order to process the devices response properly. Single crystal silicon is one of the most common materials used in inertial sensors, and it was the one chosen in this study. The properties Silicon crystal (100) are listed in Table 5.1 [53].

Table 5.1: Material properties of Silicon crystal (100) [53]

Material property	Value
Young's Modulus	131 GPa
Poisson ratio	0.28
Density	2330 kg/m <sup>3</sup>
Lamé parameter $\lambda_L$	$8.452 \times 10^{10}$ N/m <sup>2</sup>
Lamé parameter $\mu_L$	$6.641 \times 10^{10}$ N/m <sup>2</sup>

### 5.1.2.2 Modal analysis

To study MEMS inertial sensors, the knowledge of natural frequencies and the corresponding mode shapes of a device during free vibration becomes essential. Modal analysis is performed to calculate said properties, making use of FEA. The method solves an eigensystem - a group of all eigenvectors belonging to a linear transformation matched with the corresponding eigenvalue [54], the first represents the mode shape and the second represents the frequency.

The eigenvalue problem solved in this software is the following [55]:

$$[K]\{U\} = \lambda[M]\{U\} \quad (5.12)$$

In this equation,  $[K]$  stands for the stiffness matrix - obtained from the assembly of equation 5.11,  $[M]$  represents the mass matrix - assembled, taking into account the device's geometry and material density,  $\{U\}$  symbolizes the displacement function, and  $\lambda$  is the desired eigenvalue.

With the help of PETSc linear algebra package to assemble the matrices and of SLEPcEigenSolver to compute the solution to said matrices, the software can now return the eigenfrequencies related to the obtained eigenvalues:  $\lambda = \omega^2$ . The eigenvectors associated with the mentioned eigenvalues are exported to a file, which can be opened in ParaView [56] to visually analyze the mode shapes. The modal analysis implementation in this software is shown in Listings I.3 and II.3.

### 5.1.3 Electronic domain simulation

The electronic domain simulation block is the third and most variable block in the program. Every MEMS architecture possess a different system, thus requiring a different script for each design - this allows for total customization and an accurate simulation.

In this work, the analyzed devices were MEMS inertial capacitive sensors - as introduced in Subsection 3.1.1, these sensors produce a detectable signal when a



displacement causes a capacitance change between parallel plates. This general principle leads to different capacitance sensing mechanisms which have to be taken into account when implementing the software.

Two MEMS inertial sensors were simulated: a capacitive accelerometer and a linear vibratory gyroscope, as shown in Figure 5.2.

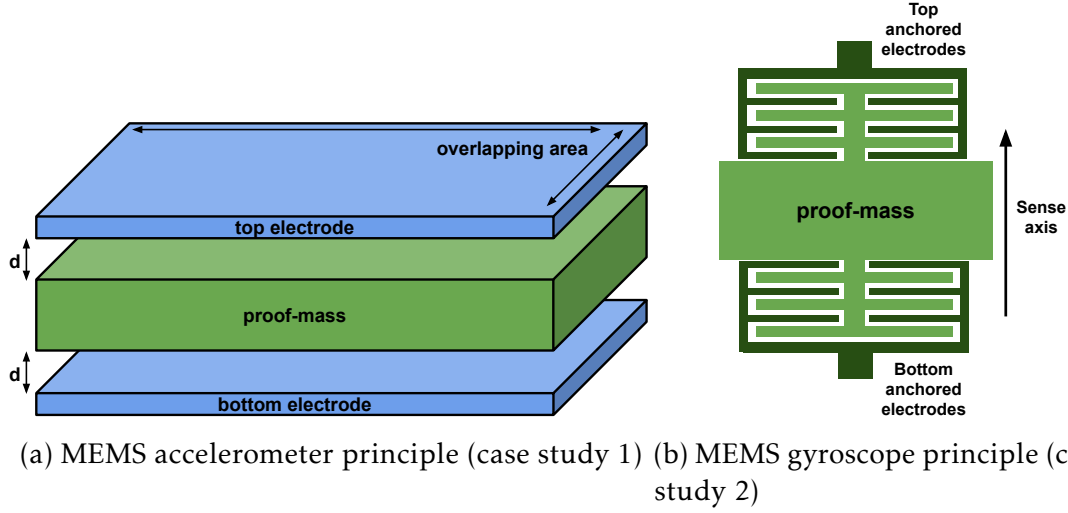


Figure 5.2: Capacitive sensing structures present in both case studies

The simulated MEMS capacitive accelerometer (Figure 5.2a) has its proof-mass between two electrodes, which results in differential sensing defined by equations (5.13),(5.14) [57]. In these Equations,  $\epsilon_0$  stands for free space permittivity and  $\epsilon_r$  represents the relative permittivity of the dielectric medium - these are listed in Table III.1. The initial vertical distance between the proof-mass and the electrodes is designated as  $d$ , and their overlapping area is  $a$ .

$$C_{top} = \frac{\epsilon_0 \epsilon_r a}{d - disp}, C_{bottom} = \frac{\epsilon_0 \epsilon_r a}{d + disp} \quad (5.13)$$

$$\Delta C = C_{top} - C_{bottom} \quad (5.14)$$

$$(5.15)$$

The linear vibratory gyroscope comprises a differential sensing mechanism as well, seen in Figure 5.2b: the proof-mass contains two sets of comb-fingers which move along the y-axis, altering the gap between the fixed electrodes and the moving ones - the capacitance change produced by this system is described by Equations (5.16),(5.17). In the aforementioned equations,  $N$  stands for the number of comb fingers,  $t$  represents the thickness,  $L$  signifies the comb fingers length, and  $d$  is the gap between said fingers.

$$C_{top} = N \frac{\epsilon_0 t L}{d - disp}, C_{bottom} = N \frac{\epsilon_0 t L}{d + disp} \quad (5.16)$$

$$\Delta C = C_{top} - C_{bottom} \approx 2N \frac{\epsilon_0 t L}{d^2} disp \quad (5.17)$$

In order to drive the gyroscope's proof-mass into driving resonance, electrostatic actuation is applied. Electrostatic actuators rely on the force between two electrodes when a voltage is applied between them [58]. Parallel-plate actuation electrodes are commonly built to apply a force in a specific direction - aligned with the desired motion direction and DoF of the target mass.

In the designed MEMS gyroscope, the implemented mechanism is the balanced actuation. The interdigitated comb-drives seen in Figure 5.3a generate the desired force by sliding parallel to each other; this force is described by Equation 5.18. A balanced actuation system illustrated in Figure 5.3b works by applying  $V_1 = V_{DC} + V_{AC}$  to one set of electrodes, and  $V_2 = V_{DC} - V_{AC}$  to the opposing set. This method allows a linearization of the force regarding a constant voltage  $V_{DC}$  and a varying  $V_{AC}$  - the electrostatic force is finally described by Equation 5.19 [7].

$$F_{comb} = \frac{-\epsilon_0 t}{d} N V^2 \quad (5.18)$$

$$F_{balanced} = 2 \frac{\epsilon_0 L t N}{d^2} V_{DC} V_{AC} \quad (5.19)$$

The aforementioned sensing and actuating equations are inserted in the software, providing the possibility to study the effects of different potential on the drive mode, and enabling the user to pass electrical performance parameters onto the genetic algorithm - thus, achieving a co-optimization.

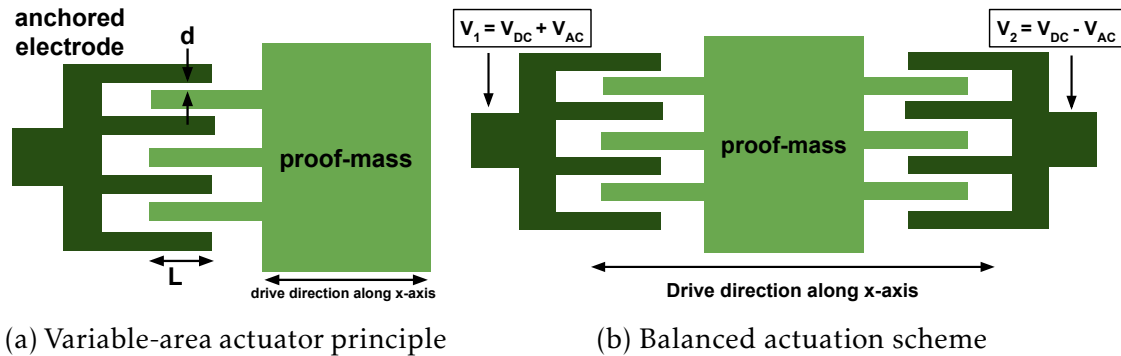


Figure 5.3: Electrostatic actuation system present in MEMS gyroscope (case study 2)

A capacitance to voltage converter is implemented in the code, in order to generate a readable electronic signal from the provoked capacitance change. The

converter is a simplified version of the converting block designed by Utz et al. [59], seen in Figure 5.4 with a governing equation stated in equation 5.20.

$$V_{C2V} = \frac{2\Delta C_s \cdot (V_{DD} - V_{cm})}{C_{int}} \quad (5.20)$$

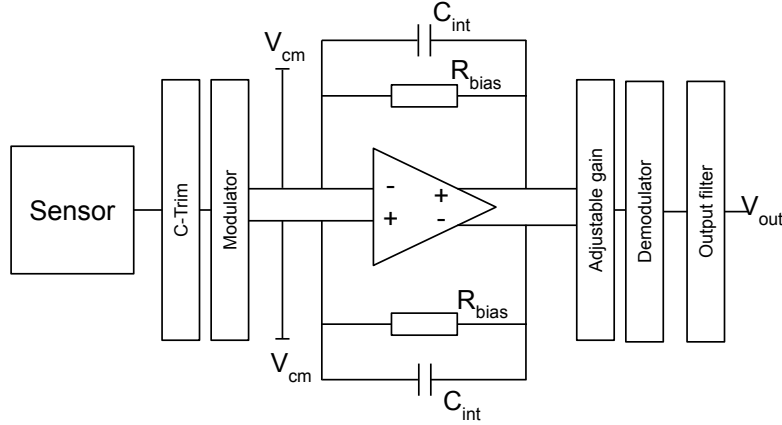


Figure 5.4: Block diagram of capacitance to voltage converter circuit implemented with both MEMS devices

In Listing I.4 and II.5, it is possible to see the implementation of the electrical domain simulation.

### 5.1.4 Damping calculation

Damping stands for the energy loss effects in any oscillatory system. In this study, the modelled damping was the viscous damping. This type of damping mechanism occurs when the gas surrounding the vibratory structures presents viscous effects caused by the internal friction of the gas trapped in the middle of vibratory structures such as comb fingers.

Viscous damping is the primary contributor to overall damping and poses as an essential parameter to be estimated [60]. In this study, squeeze film damping and slide film damping were modelled to calculate the drive and sense mode's quality-factor of both simulated devices. The simulated MEMS inertial sensors were considered to be surrounded by air ( $\epsilon_r = 1$ ).

When two parallel plates move towards each other, they squeeze the fluid (in this case, air) between them - creating a squeeze film damping phenom, seen in Figure 5.5a. Additionally, slide film damping exists when two plates slide parallel to each other - illustrated in Figure 5.5b. To model these two effects, the following equations were implemented:

$$K_n = \frac{\lambda_f}{d} \quad (5.21)$$

$$\mu_{eff_{squeeze}} = \frac{\mu}{1+9.638K_n^{1.159}} \quad (5.22)$$

$$\frac{F_c}{z} = \frac{64\sigma_s P_a A}{\pi^6 d} \sum_{m,n,odd} \frac{m^2 + c^2 n^2}{(mn)^2 [(m^2 + c^2 n^2)^2 + \sigma^2 / \pi^4]} \quad (5.23)$$

$$\sigma_s = \frac{12\mu_{eff_{squeeze}} w^2}{P_a d^2} \omega \quad (5.24)$$

$$c_{squeeze} = F_c \cdot N_{combs} \quad (5.25)$$

$$\mu_{eff_{slide}} = \frac{\mu}{1+2K_n+0.2K_n^{0.788}e^{-K_n/10}} \quad (5.26)$$

$$c_{slide} = \mu_{eff_{slide}} \frac{A}{d} \cdot N_{combs} \quad (5.27)$$

$$Q_{factor} = \frac{m_m \omega}{c} \quad (5.28)$$

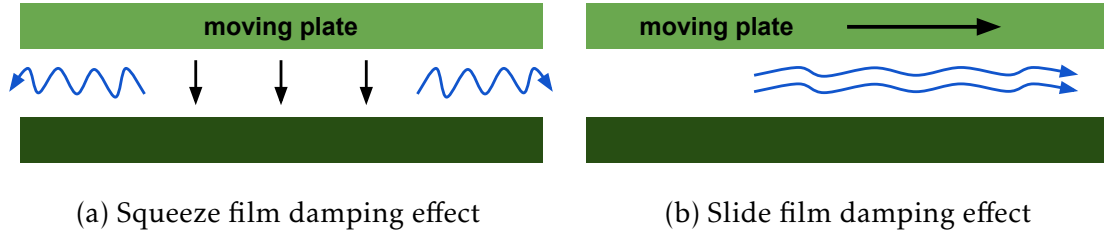


Figure 5.5: Viscous damping effects modelled in the software

In Equation 5.21,  $K_n$  represents the Knudsen number which is a measure of gas rarefaction effect - the ratio of the mean free path  $\lambda_f$  to the gap  $d$  containing the gas [61]. For squeeze film damping modelling, Equation 5.22 denotes the effective viscosity in which  $\mu$  stands for the mean viscosity (in this study, air) [62]; Equation 5.23 represents the squeeze film damping force in which  $z$  is the plate deflection,  $P_a$  is the ambient pressure, for a plate with width  $w$  and length  $l$  -  $A = wl$  and  $c = w/l$ ,  $\sigma$  is the squeeze number [63]; Equation 5.24 stands for the aforementioned squeeze number in which  $\omega$  denotes frequency; Equation 5.25 represents the viscous film damping coefficient for a sensing structure with a number of comb fingers  $N_{combs}$ .

For slide film damping modelling, Equation 5.26 refers to the effective viscosity associated with this type of damping [64], and Equation 5.27 describes the lateral damping coefficient in which  $A$  denotes the overlap area of the plates.

Equation 5.28 represents the quality factor [65, 66] associated with a movement mode, in which  $m$  stands for the mass of the moving structure,  $\omega$  denotes the frequency of vibration mode, and  $c$  is the damping coefficient associated with the movement type.

The damping calculations are implemented in the software as seen on Listing I.5 and II.4.

### 5.1.5 Genetic algorithm optimization

The GA block is the responsible for the electro-mechanical co-optimization. As explained in Section 3.2, the algorithm starts with an initial set of individuals, calculates the **figure of merit (FOM)** of each one, selects the top performers, reproduces and mutates them, and then forms the new generation.

In this study, the genetic algorithm was developed with the following workflow, demonstrated in Figure 5.6:

1. The first step of the algorithm is to initialize a first generation with 100 individuals containing the initial geometric parameters listed in each case study's section.
2. A calculation of each device's FOM is then executed - in the first generation this attribute is equal for all individuals.
3. To assemble the next generation, both an integral copy and a mutated copy of the 25 best devices are placed in the population - the remaining 50 devices are randomly mutated.
4. This process is repeated for a designated number of generations - until half of the population converges to a high-performance FOM and an individual is selected.

The genetic algorithm implementation is displayed in Listing I.6 and II.6.

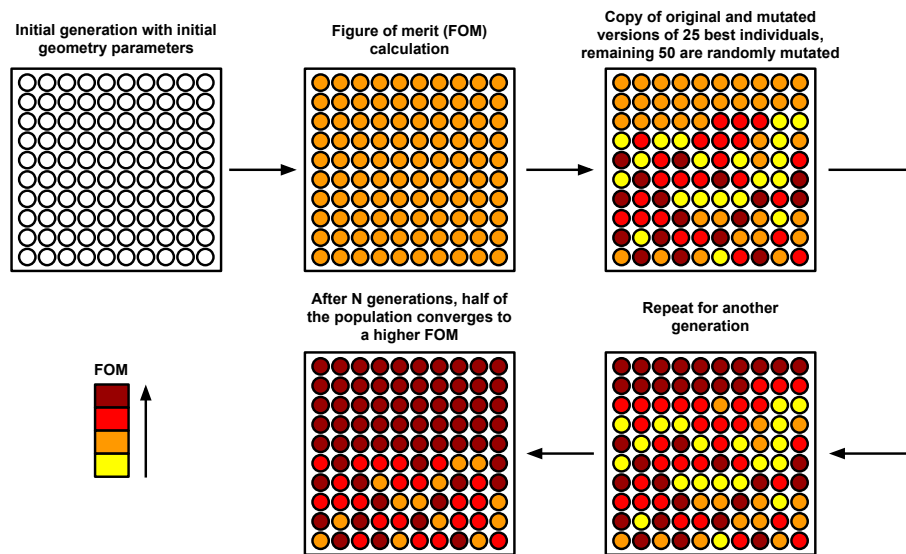


Figure 5.6: Workflow of the programmed genetic algorithm

## 5.2 Case study 1: MEMS capacitive accelerometer

As a first implementation of the developed program, an open-loop capacitive MEMS accelerometer is designed, simulated, and optimized. This device comprises four beams suspending a proof-mass above the substrate. The accelerometer is designed to detect acceleration in the  $z$ -axis by displacement of the proof-mass along said axis, with a mass-spring damper model illustrated in Figure 5.7.

To detect a capacitance change, the device's proof-mass is located between two electrodes with an overlap area equal to the proof-mass bottom and top surface area. The initial distance between the proof-mass and the electrodes is changed when the mass suffers a displacement caused by an acceleration, thus provoking a detectable capacitance change.

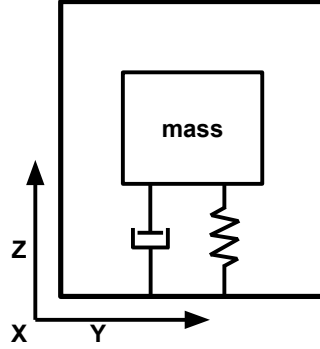


Figure 5.7: Mass-spring-damper model

### 5.2.1 Design analysis

The structure built by the developed software is illustrated in Figure 5.8, with its geometric parameters listed in Table 5.2. The device comprises four *L-shaped* beams connected to the proof-mass on one end, and fixed on the other. These beams suspend the proof-mass above the substrate, promoting a movement along the  $z$ -axis while restricting motion on the other directions - the mode shape corresponding to the natural frequency seen in Figure 5.9 confirms these characteristics.

The ruling capacitance change equation for this accelerometer is stated in Equation 5.14 and observed in Figure 5.8b, in which  $d$  is the distance between proof-mass and electrodes while  $A$  stands for the overlapping area of electrodes and proof-mass - given by the proof mass surface area.

In Table 5.2 the initial geometric parameters of the accelerometer are shown.

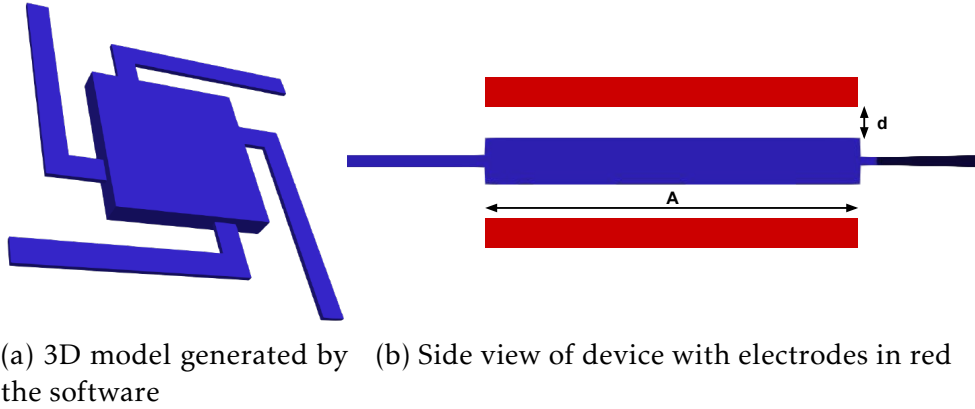


Figure 5.8: MEMS capacitive accelerometer design

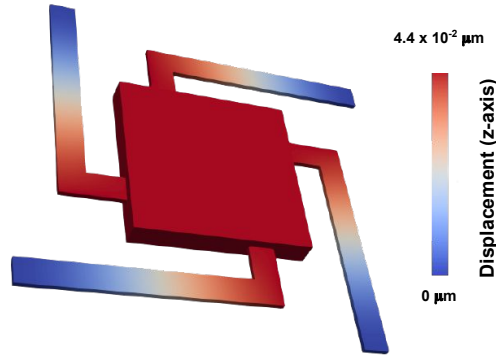


Figure 5.9: MEMS accelerometer mode shape corresponding to the natural frequency of 3284 Hz

Table 5.2: Initial geometric parameters of MEMS accelerometer

Parameter	Value
Suspension beam width	350 μm
Suspension beam length	3300 μm
Beam thickness	69 μm
Small beam length	500 μm
Proof-mass length	2400 μm
Proof-mass thickness	320 μm
Distance proof-mass/electrodes	22 μm

### 5.2.2 Optimization results

The process of simulation and optimization of the MEMS capacitive accelerometer is based on the system-level model observed in Figure 5.10.

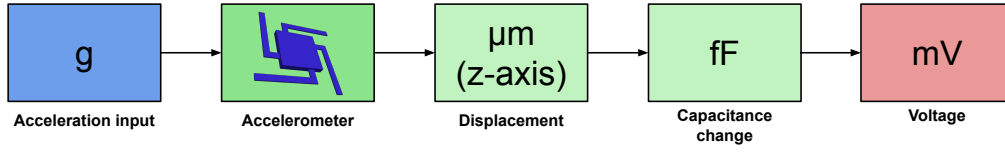


Figure 5.10: Capacitive MEMS accelerometer system-level model.

The MEMS accelerometer takes an acceleration along the z-axis as input, causing a displacement of the proof-mass that generates a detectable capacitance change, which is then read by the implemented capacitance-to-voltage circuit, governed by Equation 5.20. For the the simulated accelerometer,  $V_{DD}$  is defined as  $5V$ ,  $V_{cm} = 2.5V$ , and  $C_{int} = 300fF$ .

The solution of a PDE is strongly related to the density of the mesh. It is, therefore, necessary to perform a mesh convergence study - in this case, the natural frequency is analyzed for simulations with different numbers of meshing elements in the suspension beams. As observed in Figure 5.11, for a number of elements of 33824 - corresponding to an element size of  $55\mu m$ , the change in the first frequency mode is less than 0.15% - when compared with the next 6 points, which corresponds to a change of  $30\mu m$  in element size. Thus, the remaining simulation and optimization process will consider the optimized meshing element size.

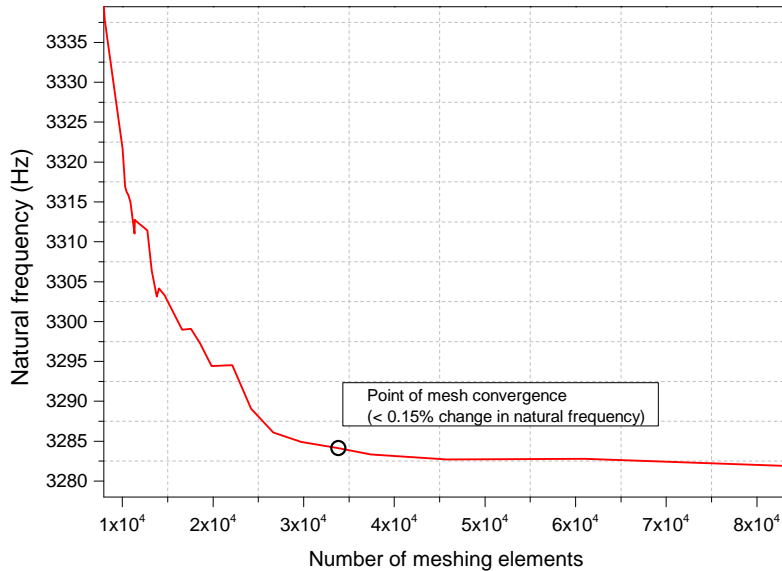


Figure 5.11: Mesh convergence study for MEMS accelerometer

The genetic algorithm optimization process described in Subsection 5.1.5 is applied to this device for 6 generations, taking into consideration a FOM defined by Equation 5.29.



$$FOM = Sensitivity(mV/g) \cdot Frequency(Hz) \cdot Q_{factor} \cdot \frac{1}{1000} \quad (5.29)$$

In this equation, *Sensitivity* stands for the output voltage when an acceleration of 1 g is applied, *Frequency* is the device's resonant frequency and  $Q_{factor}$  denotes the quality-factor of the sensing mechanism considering ambient air pressure, taking the damping into consideration.

Within 6 generations with 100 individuals each, the GA altered the chosen initial geometric parameters: proof-mass length and suspension beam width, and obtained an optimized device - the geometric changes and performance parameters are Table 5.3. The evolution of the device observed in Figure 5.12 illustrates the algorithm's tendency to reduce the suspension beam's width and to enlarge the proof-mass - this process allows for a higher sensitivity due to lower stiffness in the suspension system combined with a larger proof-mass, however, there is a decrease in the resonant frequency which limits the accelerometer bandwidth.

Table 5.3: Geometric and performance parameters of original and final accelerometer

Parameter	Original	Final	Relative change
Suspension beam width ( $\mu m$ )	350	152	-56.57%
Proof-mass length ( $\mu m$ )	2400	2613	8.15%
Sensitivity (mV/g)	80.747	237.210	193.77%
Frequency (Hz)	3284	1887	-42.54%
$Q_{factor}$	0.544	0.350	-35.66%
FOM	144.25	156.67	7.93%

The parameter changes observed in Figure 5.12 produced the performance parameters listed in Table 5.3.

To verify the accuracy of the modal analysis performed by the software, a comparison with COMSOL was made: the natural frequency obtained by COMSOL was 1897.15 Hz, while the natural frequency obtained by software was 1887.9 Hz - the difference was 0.5%, and so it was possible to assume the accuracy of the method.

The two drawbacks in the process were the reduction by 42.54% of the device's bandwidth and the decrease of the quality-factor by -35.66% - compensated by an increase of 193.77% in sensitivity and of 7.93% in FOM.

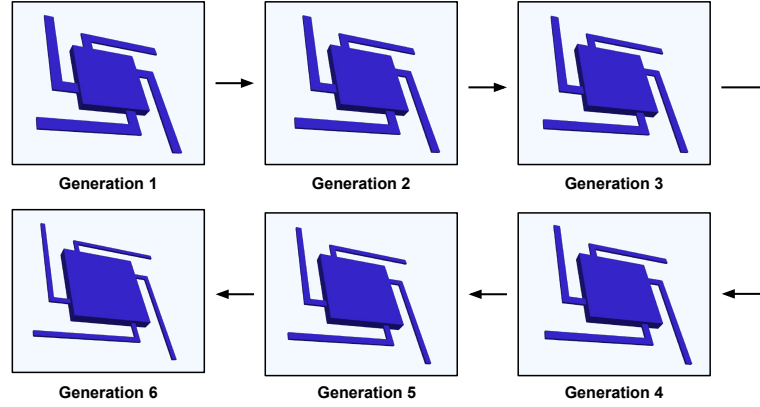


Figure 5.12: Evolution of the MEMS accelerometer through the six generations of the GA, the suspension beam width is reduced and the proof mass is enlarged

### 5.3 Case study 2: linear MEMS vibratory gyroscope

The second MEMS inertial sensor simulated and optimized with the developed software was a linear MEMS vibratory gyroscope, reproduced from [7]. This device featured a drive frame implemented to nest the proof-mass and thus decouple the drive and sense motion - this approach avoids the deflections in both modes present in regular linear suspension systems and it is illustrated in Figure 5.13. An *u-beam* suspension system was put together in order to ensure that both the drive and sense motion only deflect in the correct direction.

The working principle of MEMS vibratory gyroscopes was introduced in Subsection 3.1.2: these devices maintain a drive oscillation that allows for the detection of the Coriolis force generated by an angular rate input - the force will result in an energy transfer from the drive axis to the sense axis which occurs in the form of a proof-mass movement along said axis.

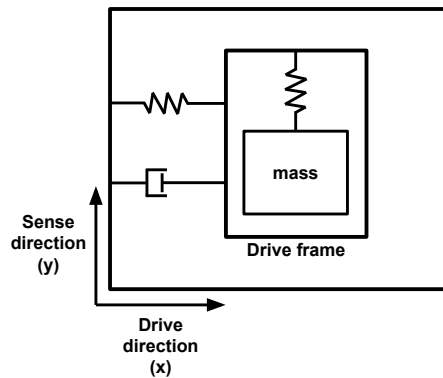
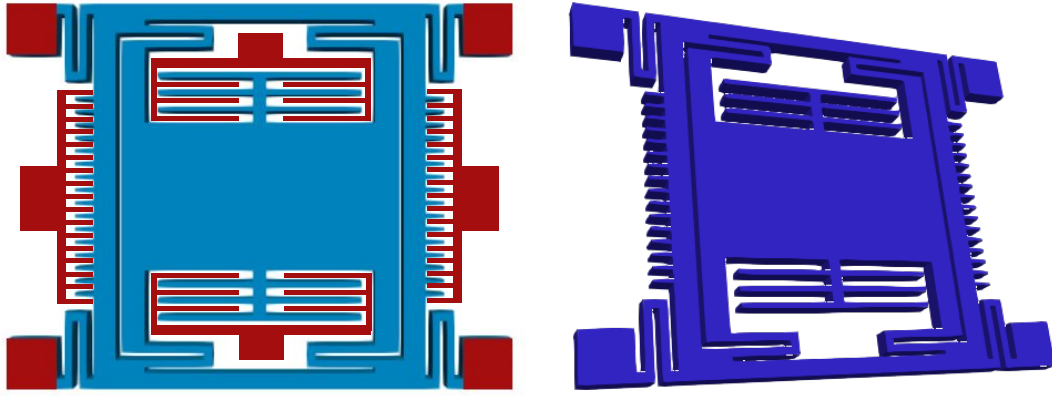


Figure 5.13: Mass-spring-damper model of MEMS gyroscope design

### 5.3.1 Design analysis

The geometry built by the software is shown in Figure 5.14, with initial geometric parameters listed in Table 5.4. This design comprises eight anchors: four of them anchoring the suspension *u-beams* connected to the drive frame, two stationary electrodes for sensing, and two stationary drive electrodes.

The *u-beams* are designed to perform as a suspension system that keep the proof-mass above the substrate while eliminating nonlinearity and axial-loading limitations present in the simple single fixed beams. The four drive frame beams promote movement along the x-axis - the drive direction, and the four beams that connect the proof-mass to the drive frame facilitate a displacement by the y-axis - the sense direction.



(a) MEMS gyroscope design, with stationary parts in red (b) 3D model generated by the software

Figure 5.14: Linear vibratory MEMS gyroscope design [7]

Table 5.4: Initial geometric parameters of MEMS gyroscope

Parameter	Value
Suspension beam width	20 $\mu\text{m}$
Suspension beam length	194 $\mu\text{m}$
Drive frame length	970 $\mu\text{m}$
Proof-mass lateral beam width	60 $\mu\text{m}$
Proof-mass lateral beam length	430 $\mu\text{m}$
Proof-mass width	580 $\mu\text{m}$
Proof-mass length	440 $\mu\text{m}$
Comb finger width	14 $\mu\text{m}$
Drive comb finger length	48 $\mu\text{m}$
Sense comb finger length	243 $\mu\text{m}$
Thickness	50 $\mu\text{m}$

In this gyroscope, drive oscillation along the x-axis was possible due to balanced variable-area electrostatic actuation, which was done through the lateral electrodes seen in Figure 5.14a. The sensing principle applied in the device was the differential sensing, made possible by two sets of variable-gap comb-fingers observed inside the drive frame.

### 5.3.2 Optimization results

The simulation and optimization of the linear vibratory MEMS gyroscope is based on the system-level model illustrated in Figure 5.15.

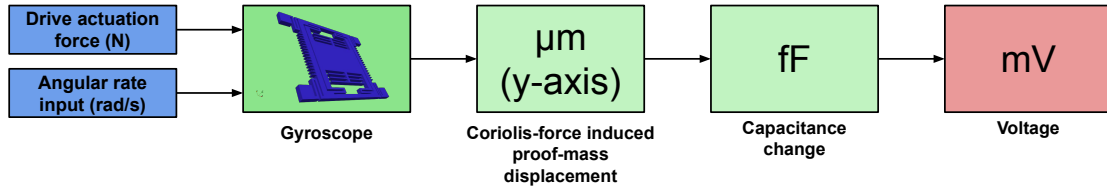


Figure 5.15: Linear vibratory MEMS gyroscope system-level model.

The device takes a drive actuation force governed by Equation 5.19 and generated by the aforementioned driving electrodes, as well as an angular-rate around the z-axis as input. The software takes the drive actuation force and simulates its effect on the MEMS structure, taking into consideration damping (in this mechanism, slide-film damping is the most prominent damping factor), and obtaining the resulting drive amplitude. For this actuation mechanism, a DC voltage of 8V and an AC voltage of 4V are applied.

The gyroscope then makes use of the driving velocity along the x-axis and the angular rate input to generate a Coriolis force along the y-axis, providing a displacement of the proof-mass. This displacement causes a detectable capacitance change, described by Equation 5.17, which is then read by the implemented capacitance-to-voltage circuit, governed by Equation 5.20. For the simulated gyroscope,  $V_{DD}$  is defined as 5V,  $V_{cm} = 2.5V$ , and  $C_{int} = 100fF$ .

For this gyroscope, the first frequency mode is analyzed for simulations with different numbers of meshing elements. As observed in Figure 5.16, for a number of elements of 9737 - corresponding to an element size of  $80\mu m$ , the change in the first frequency mode is less than 0.15% - when compared with the next 6 points, which corresponds to a change of  $30\mu m$  in element size. Thus, the remaining simulation and optimization process will consider the optimized meshing element size.

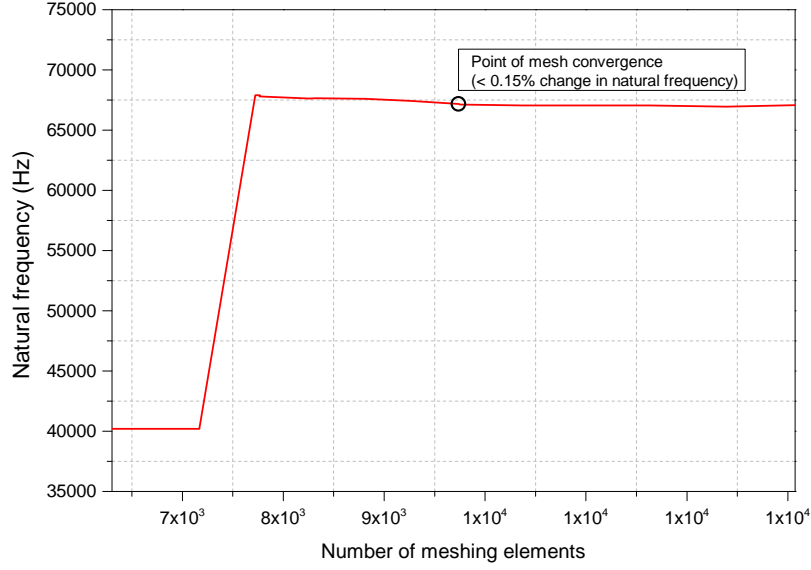


Figure 5.16: Mesh convergence study for MEMS gyroscope

The genetic algorithm optimization process described in Subsection 5.1.5 is applied to this device for 6 generations. The FOM considered by the GA is defined by Equation 5.30.

$$FOM = (Sensitivity(mV/rads^{-1}) \cdot \frac{1}{\Delta f} \cdot Q_{sense}) \cdot 10^6 \quad (5.30)$$

In this equation, *Sensitivity* is given by the output voltage when the device is subjected to an angular rate of  $1rads^{-1}$  around the z-axis,  $\Delta f$  denotes the difference between drive and sense frequency - this parameter is of importance to achieve maximum mechanical gain in the sense mode concerning the input angular rate. Looking at Equation 5.31 [7], it becomes clear that it is desirable to match drive and sense resonant frequencies. Lastly,  $Q_{sense}$  represents the sense mode quality factor.

$$y_0 = \Omega_z \frac{m_C \omega_D}{m_S \omega_S^2} \frac{2x_0}{\sqrt{[1 - (\frac{\omega_D}{\omega_S})^2] + [\frac{1}{Q_{sense}} \frac{\omega_D}{\omega_S}]^2}} \quad (5.31)$$

During the 6 generations with 100 individuals, the algorithm altered the chosen initial geometric parameters to find the optimal device - the geometric changes and performance parameters are listed in Table 5.5. The chosen parameters were: suspension beam's width, proof-mass width and length, proof-mass frame width and length, and sense comb fingers width. The evolution of the optimization is illustrated in Figure 5.17, in which the best device from each generation is displayed.

The suspension beam's width saw a severe reduction (similarly to the accelerometer's springs), on the other hand, the optimized proof-mass became larger than the original - this combination leads to an increase in compliancy of the whole structure, and thus, in sensitivity. Moreover, the drive and sense mode frequencies as well as the frequency split were significantly reduced. A comparison between frequency modes of the original and optimized device is shown in Figure 5.18.

Table 5.5: Geometric and performance parameters of original and optimized gyroscope

Parameter	Original	Final	Relative change
Suspension beam width ( $\mu m$ )	20	9	-55.00%
Proof-mass frame width ( $\mu m$ )	430	395	-8.14%
Proof-mass frame length ( $\mu m$ )	60	54	-10.00%
Proof-mass width ( $\mu m$ )	290	309	6.15%
Proof-mass length ( $\mu m$ )	220	240	8.33%
Sense finger width ( $\mu m$ )	14	9	-35.71%
Sensitivity ( $mV/rads^{-1}$ )	1.546	8.054	420.9%
$\Delta f$	13296	5792	-56.44%
$Q_{sense}$	1.917	0.952	-50.34%
FOM	222.9	1323	493.5%

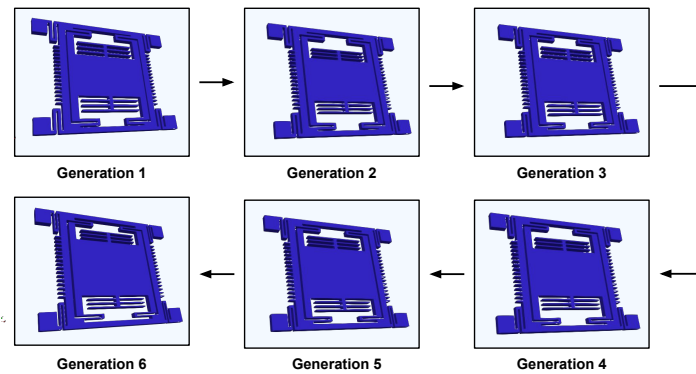


Figure 5.17: Evolution of the MEMS gyroscope through the six generations of the GA - the proof-mass became larger; the u-beams, the sense comb fingers, and the proof-mass frame became thinner

The frequency mode shapes illustrated in Figure 5.18 represent the magnitude of movement in the x-axis for a driving motion, or in the y-axis for a sensing motion. It becomes visible that in the optimized device, the undesired y-axis movement in the drive frame is reduced, while the desired proof-mass displacement is slightly enhanced.

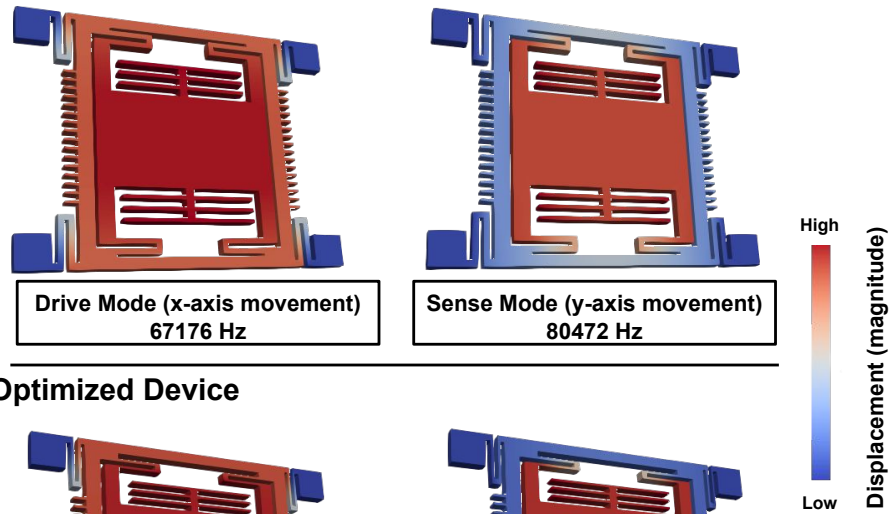
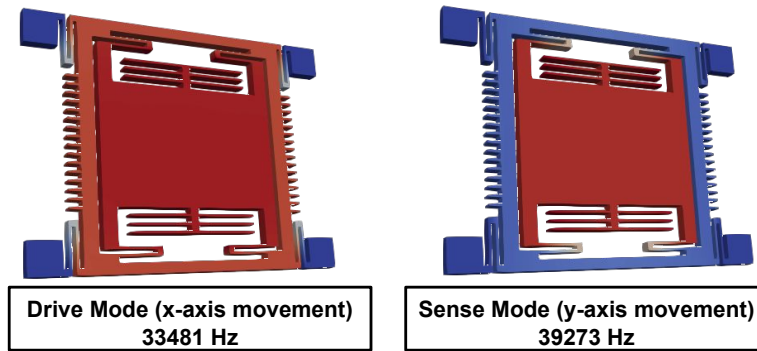
**Original Device****Optimized Device**

Figure 5.18: Frequency modes of original and optimized MEMS gyroscope, the movement modes became more pronounced

The changes observed in Figure 5.17 produced the performance changes listed in Table 5.5. The only drawback of the optimization process was the decrease of 50.34% in the sense mode's quality factor - it was largely compensated by a 420.9% increase in sensitivity and by a decrease of 56.44% in frequency mismatch. Overall, the FOM improved by 493.5%.





## CONCLUSION AND FUTURE PERSPECTIVES

The advent of micromachining technology brought a never-ending range of possible applications for micro-sized sensors. In the inertial sensor's area, the experienced growth opens the door to numerous improvements in quality of life as well as life-saving applications in the automotive industry. This array of new technologies in fabrication and product possibilities would benefit from a similar development in the process of design, simulation and optimization.

This study presented a novel electro-mechanical co-optimization methodology for MEMS inertial sensors, entirely based on Python. A software comprising geometry design, a finite element method simulation, damping calculation, electronic domain simulation, and a genetic algorithm optimization process - was developed and applied to two MEMS inertial sensors.

The software can build geometries with relative complexity, making use of the *Pygmsh* Python library. Although the most complex geometric operations such as fillet, chamfer, bezier curve, and arrays are not available; the vast majority of MEMS inertial sensors can be built by code within the software.

The geometry building block passes its parameters and mesh to the FEM part of the program, which is able to process modal analysis and displacement accurately - with a reported 0.5% difference to the frequency modes obtained with COMSOL.

The damping script takes into account the geometric parameters and the results from the modal analysis, calculating the squeeze film and slide film damping coefficient, and later the quality factor.

Depending on what type of actuation or sensing the device has, the electronic block of the software calculates the capacitance change, passing the values to the implemented circuit which in turn computes the voltage output of the system.

Finally, the implemented genetic algorithm takes the performance parameters of the devices and proceeds to select the best individuals out of each generation, achieving a co-optimized sensor in the end. To validate the software, two MEMS inertial sensors were designed, simulated and optimized.

The first optimized device was an open-loop capacitive MEMS accelerometer:

the co-optimization process increased the sensitivity by 193.77% and the FOM by 7.93%, compensating for the loss of 42.54% in resonant frequency and of 35.66%. The first version of this implementation resulted in a publication titled “Electro-mechanical Co-Optimization of MEMS Devices in Python” - submitted, accepted, and presented at IEEE SENSORS 2020 conference.

The second optimized device was an open-loop Coriolis vibratory MEMS gyroscope: the co-optimization process improved the sensitivity by 420.9% and the frequency mismatch decreased by 56.44%, compensating the 50.34% loss in the quality-factor and producing an overall improvement in FOM of 493.5%. The co-optimization of this device resulted in a publication titled “Python-based Electro-mechanical Co-optimization of MEMS Inertial Sensors” - submitted to IEEE MEMS21 conference.

The developed Python solution is a powerful tool that provides designers with limitless customization freedom, presenting engineers with complete control of all steps in simulation and optimization - allowing an efficient management of computational resources according to specific research goals.

In order for this software to become of professional-grade, it is necessary to implement transient and closed-loop system simulation and optimization. Also, a non-linearity calculation and integration into the software is essential if the goal is to simulate the real performance of the devices

## BIBLIOGRAPHY

- [1] D. K. Shaeffer. “MEMS inertial sensors: A tutorial overview.” In: *IEEE Communications Magazine* 51.4 (2013), pp. 100–109.
- [2] C. Acar, A. R. Schofield, A. A. Trusov, L. E. Costlow, and A. M. Shkel. “Environmentally Robust MEMS Vibratory Gyroscopes for Automotive Applications.” In: *IEEE Sensors Journal* 9.12 (2009), pp. 1895–1906.
- [3] Y. Dong. “8 - MEMS inertial navigation systems for aircraft.” In: *MEMS for Automotive and Aerospace Applications*. Ed. by M. Kraft and N. M. White. Woodhead Publishing Series in Electronic and Optical Materials. Woodhead Publishing, 2013, pp. 177–219. ISBN: 978-0-85709-118-5. DOI: <https://doi.org/10.1533/9780857096487.2.177>. URL: <http://www.sciencedirect.com/science/article/pii/B9780857091185500084>.
- [4] G. Bhatt, K. Manoharan, P. S. Chauhan, and S. Bhattacharya. “MEMS Sensors for Automotive Applications: A Review.” In: *Sensors for Automotive and Aerospace Applications*. Ed. by S. Bhattacharya, A. K. Agarwal, O. Prakash, and S. Singh. Singapore: Springer Singapore, 2019, pp. 223–239. ISBN: 978-981-13-3290-6. DOI: [10.1007/978-981-13-3290-6\\_12](https://doi.org/10.1007/978-981-13-3290-6_12). URL: [https://doi.org/10.1007/978-981-13-3290-6\\_12](https://doi.org/10.1007/978-981-13-3290-6_12).
- [5] B. A. Abruzzo and T. G. Recchia. “Online Calibration of Inertial Sensors for Range Correction of Spinning Projectiles.” In: *Journal of Guidance, Control, and Dynamics* 39.8 (2016), pp. 1918–1924. DOI: [10.2514/1.G001809](https://doi.org/10.2514/1.G001809). eprint: <https://doi.org/10.2514/1.G001809>. URL: <https://doi.org/10.2514/1.G001809>.
- [6] J. S. Han, E. B. Rudnyi, and J. G. Korvink. “Efficient optimization of transient dynamic problems in MEMS devices using model order reduction.” In: *Journal of Micromechanics and Microengineering* 15.4 (Mar. 2005), pp. 822–832. DOI: [10.1088/0960-1317/15/4/021](https://doi.org/10.1088/0960-1317/15/4/021). URL: <https://doi.org/10.1088/0960-1317/15/4/021>.

- [7] C. Acar and A. Shkel. *MEMS vibratory gyroscopes: structural approaches to improve robustness*. Springer Science & Business Media, 2008.
- [8] T. Masuzawa. “State of the art of micromachining.” In: *Cirp Annals* 49.2 (2000), pp. 473–488.
- [9] S. Beeby, G. Ensel, N. White, and M. Kraft. *MEMS Mechanical Sensors*. Artech House MEMS Library. Artech House, 2004. ISBN: 9781580535366. URL: <https://books.google.be/books?id=iOUwDwAAQBAJ>.
- [10] Guan Xin, Yan Dong, and Gao Zhen-hai. “Study on errors compensation of a vehicular MEMS accelerometer.” In: *IEEE International Conference on Vehicular Electronics and Safety, 2005*. 2005, pp. 205–210. DOI: [10.1109/ICVES.2005.1563642](https://doi.org/10.1109/ICVES.2005.1563642).
- [11] S. D. Senturia. “Perspectives on MEMS, past and future: the tortuous pathway from bright ideas to real products.” In: *TRANSDUCERS '03. 12th International Conference on Solid-State Sensors, Actuators and Microsystems. Digest of Technical Papers (Cat. No.03TH8664)*. Vol. 1. 2003, 10–15 vol.1. DOI: [10.1109/SENSOR.2003.1215241](https://doi.org/10.1109/SENSOR.2003.1215241).
- [12] D. Glassbrenner and M. Starnes. *Lives saved calculations for seat belts and frontal air bags*. Washington, DC: National Highway Traffic Safety Administration, 2009.
- [13] J. Marek. “MEMS for automotive and consumer electronics.” In: *2010 IEEE International Solid-State Circuits Conference-(ISSCC)*. IEEE. 2010, pp. 9–17.
- [14] S. Kusmakar, C. K. Karmakar, B. Yan, T. J.O’Brien, R. Muthuganapathy, and M. Palaniswami. “Automated Detection of Convulsive Seizures Using a Wearable Accelerometer Device.” In: *IEEE Transactions on Biomedical Engineering* 66.2 (2019), pp. 421–432. DOI: [10.1109/TBME.2018.2845865](https://doi.org/10.1109/TBME.2018.2845865).
- [15] A. Sucerquia, J. D. López, and J. F. Vargas-Bonilla. “Real-life/real-time elderly fall detection with a triaxial accelerometer.” In: *Sensors* 18.4 (2018), p. 1101.
- [16] S. B. Khojasteh, J. R. Villar, C. Chira, V. M. González, and E. De la Cal. “Improving fall detection using an on-wrist wearable accelerometer.” In: *Sensors* 18.5 (2018), p. 1350.

- [17] P. Van Thanh, D.-T. Tran, D.-C. Nguyen, N. D. Anh, D. N. Dinh, S. El-Rabaie, and K. Sandrasegaran. "Development of a real-time, simple and high-accuracy fall detection system for elderly using 3-DOF accelerometers." In: *Arabian Journal for Science and Engineering* 44.4 (2019), pp. 3329–3342.
- [18] M. Dencker and L. B. Andersen. "Accelerometer-measured daily physical activity related to aerobic fitness in children and adolescents." In: *Journal of sports sciences* 29.9 (2011), pp. 887–895.
- [19] Guangchun Li, Yunfeng He, Yanhui Wei, Shenbo Zhu, and Yanzhe Cao. "The MEMS gyro stabilized platform design based on Kalman Filter." In: *2013 International Conference on Optoelectronics and Microelectronics (ICOM)*. 2013, pp. 14–17. DOI: [10.1109/ICoOM.2013.6626480](https://doi.org/10.1109/ICoOM.2013.6626480).
- [20] V. Kempe. *Inertial MEMS: Principles and Practice*. Cambridge University Press, 2011, pp. 14–24. ISBN: 9781139494823. URL: <https://books.google.be/books?id=XzdvDGBLZ8EC>.
- [21] M. Armenise, C. Ciminelli, F. Dell’Olio, and V. Passaro. *Advances in Gyroscope Technologies*. Springer Berlin Heidelberg, 2010. ISBN: 9783642154942. URL: <https://books.google.be/books?id=1JUiyigJRBgC>.
- [22] W. Somerville. "The description of Foucault’s pendulum." In: *Quarterly Journal of the Royal Astronomical Society* 13 (1972), pp. 40–62.
- [23] A. Persson. "The Coriolis Effect—a conflict between common sense and mathematics." In: *Italian Meteorological Society* (2005), pp. 20–31.
- [24] V. Apostolyuk. *Coriolis Vibratory Gyroscopes: Theory and Design*. Springer International Publishing, 2015. ISBN: 9783319221984. URL: <https://books.google.be/books?id=hBRcCgAAQBAJ>.
- [25] C. Darwin. *The origin of species*. PF Collier & son New York, 1909.
- [26] G. Mendel. *Experiments in plant hybridisation*. Harvard University Press, 1965.
- [27] D. S. Weile and E. Michielssen. "Genetic algorithm optimization applied to electromagnetics: A review." In: *IEEE Transactions on Antennas and Propagation* 45.3 (1997), pp. 343–353.
- [28] Y. Zhang, R. Kamalian, A. M. Agogino, and C. H. Séquin. "Hierarchical MEMS synthesis and optimization." In: *Smart Structures and Materials 2005: Smart Electronics, MEMS, BioMEMS, and Nanotechnology*. Vol. 5763. International Society for Optics and Photonics. 2005, pp. 96–106.

- [29] J. S. Han, E. B. Rudnyi, and J. G. Korvink. “Efficient optimization of transient dynamic problems in MEMS devices using model order reduction.” In: *Journal of Micromechanics and Microengineering* 15.4 (2005), p. 822.
- [30] E. S. Hung, Y.-J. Yang, and S. D. Senturia. “Low-order models for fast dynamical simulation of MEMS microstructures.” In: *Proceedings of International Solid State Sensors and Actuators Conference (Transducers’ 97)*. Vol. 2. IEEE. 1997, pp. 1101–1104.
- [31] M. Kudryavtsev, E. B. Rudnyi, J. G. Korvink, D. Hohlfeld, and T. Bechtold. “Computationally efficient and stable order reduction methods for a large-scale model of MEMS piezoelectric energy harvester.” In: *Microelectronics Reliability* 55.5 (2015), pp. 747–757.
- [32] A. H. Nayfeh, M. I. Younis, and E. M. Abdel-Rahman. “Reduced-order models for MEMS applications.” In: *Nonlinear dynamics* 41.1-3 (2005), pp. 211–236.
- [33] C. Wang, H. Liu, X. Song, F. Chen, I. Zeimpekis, Y. Wang, J. Bai, K. Wang, and M. Kraft. “Genetic algorithm for the design of freeform geometries in a MEMS accelerometer comprising a mechanical motion pre-amplifier.” In: *2019 20th International Conference on Solid-State Sensors, Actuators and Microsystems & Eurosensors XXXIII (TRANSDUCERS & EUROSENSORS XXXIII)*. IEEE. 2019, pp. 2099–2102.
- [34] S. COMSOL AB Stockholm. *COMSOL Multiphysics®*. Version 5.4. URL: [www.comsol.com](http://www.comsol.com).
- [35] I. The Mathworks. *MATLAB:2017b*. Natick, Massachusetts, 2017.
- [36] M. R. Solouk, M. H. Shojaeefard, and M. Dahmardeh. “Parametric topology optimization of a MEMS gyroscope for automotive applications.” In: *Mechanical Systems and Signal Processing* 128 (2019), pp. 389–404. ISSN: 0888-3270. DOI: <https://doi.org/10.1016/j.ymssp.2019.03.049>.
- [37] J. T. Oden. “Finite Elements : Introduction.” In: *Handbook of Numerical Analysis Volime II : Finite Element Methods (Part1)* (1991), pp. 3–12.
- [38] J. Fritz. *Partial Differential Equations*. New York: Springer-Verlag, 1982. ISBN: 0-387-90609-6.
- [39] A. Logg, K.-A. Mardal, G. N. Wells, et al. *Automated Solution of Differential Equations by the Finite Element Method*. Ed. by A. Logg, K.-A. Mardal, and G. N. Wells. Springer, 2012. ISBN: 978-3-642-23098-1. DOI: [10.1007/978-3-642-23099-8](https://doi.org/10.1007/978-3-642-23099-8).

- [40] G. Van Rossum and F. L. Drake. *Python 3 Reference Manual*. Scotts Valley, CA: CreateSpace, 2009. ISBN: 1441412697.
- [41] K. J. Millman and M. Aivazis. “Python for Scientists and Engineers.” In: *Computing in Science Engineering* 13.2 (2011), pp. 9–12.
- [42] T. E. Oliphant. “Python for Scientific Computing.” In: *Computing in Science Engineering* 9.3 (2007), pp. 10–20.
- [43] N. Schlömer, A. Cervone, G. McBain, Tryfon-Mw, R. V. Staden, F. Gokstorp, Toothstone, J. S. Dokken, Anzil, and J. Sanchez. *nschloe/pygmsh v6.1.1*. 2020. DOI: [10.5281/zenodo.3764683](https://doi.org/10.5281/zenodo.3764683).
- [44] C. Geuzaine and J.-F. Remacle. “Gmsh: a three-dimensional finite element mesh generator with built-in pre- and post-processing facilities.” In: *International Journal for Numerical Methods in Engineering* 79.11 (2009), pp. 1309–1331.
- [45] N. Schlömer, G. McBain, K. Luu, christos, T. Li, V. M. Ferrándiz, C. Barnes, L. Dalcin, eolianoe, and nilswagner. *nschloe/meshio v4.0.12*. 2020. DOI: [10.5281/zenodo.3773318](https://doi.org/10.5281/zenodo.3773318).
- [46] M. S. Alnæs, J. Blechta, J. Hake, A. Johansson, B. Kehlet, A. Logg, C. Richardson, J. Ring, M. E. Rognes, and G. N. Wells. “The FEniCS Project Version 1.5.” In: *Archive of Numerical Software* 3.100 (2015). DOI: [10.11588/ans.2015.100.20553](https://doi.org/10.11588/ans.2015.100.20553).
- [47] A. Logg and G. N. Wells. “DOLFIN: Automated Finite Element Computing.” In: *ACM Transactions on Mathematical Software* 37.2 (2010). DOI: [10.1145/1731022.1731030](https://doi.org/10.1145/1731022.1731030).
- [48] A. Lurie and A. Belyaev. *Theory of Elasticity*. Foundations of Engineering Mechanics. Springer Berlin Heidelberg, 2010, pp. 151–155. ISBN: 9783540264552. URL: [https://books.google.be/books?id=sEqz%5C\\_LKkdEC](https://books.google.be/books?id=sEqz%5C_LKkdEC).
- [49] J. Brewer. “Divergence of a vector field.” In: *Vector Calculus* 7 (1999).
- [50] D. R. Smith. “The Cauchy Stress Tensor.” In: *An Introduction to Continuum Mechanics — after Truesdell and Noll*. Dordrecht: Springer Netherlands, 1993, pp. 143–162. ISBN: 978-94-017-0713-8. DOI: [10.1007/978-94-017-0713-8\\_5](https://doi.org/10.1007/978-94-017-0713-8_5). URL: [https://doi.org/10.1007/978-94-017-0713-8\\_5](https://doi.org/10.1007/978-94-017-0713-8_5).
- [51] Z.-C. S. K. Feng. *Mathematical Theory of Elastic Structures*. Springer New York, 1981, pp. 106–108. ISBN: 0-387-51326-4.

- [52] A. H.-D. Cheng and D. T. Cheng. “Heritage and early history of the boundary element method.” In: *Engineering Analysis with Boundary Elements* 29.3 (2005), pp. 268–302.
- [53] J. Wortman and R. Evans. “Young’s modulus, shear modulus, and Poisson’s ratio in silicon and germanium.” In: *Journal of applied physics* 36.1 (1965), pp. 153–156.
- [54] W. H. Press, S. A. Teukolsky, W. T. Vetterling, and B. P. Flannery. *Numerical recipes 3rd edition: The art of scientific computing*. Cambridge university press, 2007.
- [55] R. Clough and J. Penzien. *Dynamics of Structures*. McGraw-Hill, 1993, p. 201. ISBN: 9780071132411. URL: <https://books.google.be/books?id=HxLakQEACAAJ>.
- [56] U. Ayachit. *The ParaView Guide: A Parallel Visualization Applications*. Kitware, 2015. ISBN: 978-1930934306.
- [57] R. F. Harrington. *Introduction to electromagnetic engineering*. Courier Corporation, 2003.
- [58] R. W. Johnstone and M. Parameswaran. “Electrostatic Actuators.” In: *An Introduction to Surface-Micromachining*. Springer, 2004, pp. 135–152.
- [59] A. Utz, C. Walk, N. Haas, T. Fedtschenko, A. Stanitzki, M. Mokhtari, M. Görtz, M. Kraft, and R. Kokozinski. “An ultra-low noise capacitance to voltage converter for sensor applications in 0.35  $\mu\text{m}$  CMOS.” In: *Journal of Sensors and Sensor Systems* 6.2 (2017), pp. 285–301.
- [60] M. Bao and H. Yang. “Squeeze film air damping in MEMS.” In: *Sensors and Actuators A: Physical* 136.1 (2007), pp. 3–27.
- [61] Springer Verlag GmbH, European Mathematical Society. *Encyclopedia of Mathematics: Knudsen Number*. Website. URL: [http://encyclopediaofmath.org/index.php?title=Knudsen\\_number&oldid=13592](http://encyclopediaofmath.org/index.php?title=Knudsen_number&oldid=13592).
- [62] T. Veijola, H. Kuisma, J. Lahdenperä, and T. Ryhänen. “Equivalent-circuit model of the squeezed gas film in a silicon accelerometer.” In: *Sensors and Actuators A: Physical* 48.3 (1995), pp. 239–248.
- [63] J. J. Blech. “On isothermal squeeze films.” In: (1983).
- [64] T. Veijola and M. Turowski. “Compact damping models for laterally moving microstructures with gas-rarefaction effects.” In: *Journal of Microelectromechanical Systems* 10.2 (2001), pp. 263–273.



- [65] W. Siebert. *Circuits, Signals, and Systems*. MIT electrical engineering and computer science series. McGraw-Hill, 1986. ISBN: 9780262192293. URL: <https://books.google.be/books?id=zBTUiIrb2WIC>.
- [66] D. Alciatore and M. Hstand. *Introduction to Mechatronics and Measurement Systems*. Engineering Series. McGraw-Hill Companies, Incorporated, 2007. ISBN: 9780072963052. URL: <https://books.google.be/books?id=VOFSAAAAMAAJ>.





## SOFTWARE IMPLEMENTATION ON MEMS ACCELEROMETER

The developed software code, implemented on a MEMS accelerometer, is displayed on the following listings. Several software packages and Python libraries are necessary in order to run the program:

- Software packages: *Gmsh*
- Python libraries: *Pygmsh*, *meshio*, *FEniCS*, *math*, *numpy*, *random*, *copy*

The user should build the initial device in the geometry building script and adapt the following simulation and optimization scripts to the geometric parameters of said device - finally the program is ran from the genetic algorithm script.

Listing I.1: Geometry building block

```

1  # MEMS Accelerometer 3D Geometry
2  # @ruiesteves
3
4  # Imports
5  import pygmsh as pg # geometry & meshing definition
6  import meshio # meshing export
7
8
9  # Functions
10 def build(suspension_beam_width,proof_mass_length):
11
12     # Geometric parameters
13     cl = 55
14     proof_mass_cl = 150
15     scale = 1e-6
16     suspension_beam_length = 3300*scale
17     beam_thickness = 69*scale
18     small_beam_length = 500*scale
19     proof_mass_thickness = 320*scale
20     beam_dist = 500*scale
21     beam_l = 122.5 * scale

```

```

22     beam_h = 177.5 * scale
23     beam_dist2 = beam_dist + suspension_beam_length
24     beam_dist3 = proof_mass_length + suspension_beam_width + small_beam_length
25     beam_dist_final = beam_dist2 - beam_dist3
26     beam_lower = (proof_mass_thickness - beam_thickness)/2
27     beam_to_mass = (beam_dist_final+suspension_beam_width+small_beam_length +
    ↪ proof_mass_length) - suspension_beam_length
28
29     # Geometry build
30     geom = pg.opencascade.Geometry()
31
32     # Beam1_1
33     p1 = [0,beam_dist_final,beam_lower]
34     p2 = [suspension_beam_length,suspension_beam_width,beam_thickness]
35     beam1_1 = geom.add_box(p1,p2,char_length=c1*scale)
36
37     # Beam1_2
38     p3 = [suspension_beam_length-suspension_beam_width,beam_dist_final +
    ↪ suspension_beam_width,beam_lower]
39     p4 = [suspension_beam_width,small_beam_length,beam_thickness]
40     beam1_2 = geom.add_box(p3,p4,char_length=c1*scale)
41
42     # Beam1 complete
43     beam1 = geom.boolean_union([beam1_1,beam1_2])
44
45     # Proof mass
46     p1 = [beam_dist_final+suspension_beam_width+small_beam_length,
    ↪ beam_dist_final+suspension_beam_width+small_beam_length,0]
47     p2 = [proof_mass_length,proof_mass_length,proof_mass_thickness]
48     proof_mass = geom.add_box(p1,p2,char_length=proof_mass_c1*scale)
49
50     # Beam2_1
51     p1 = [beam_dist_final,beam_dist_final+suspension_beam_width+
    ↪ small_beam_length+beam_to_mass,beam_lower]
52     p2 = [suspension_beam_width,suspension_beam_length,beam_thickness]
53     beam2_1 = geom.add_box(p1,p2,char_length=c1*scale)
54
55     # Beam2_2
56     p1 = [beam_dist_final+suspension_beam_width,beam_dist_final+
    ↪ suspension_beam_width+small_beam_length+beam_to_mass,beam_lower]
57     p2 = [small_beam_length,suspension_beam_width,beam_thickness]
58     beam2_2 = geom.add_box(p1,p2,char_length=c1*scale)
59
60     # Beam 2
61     beam2 = geom.boolean_union([beam2_1,beam2_2])

```

```

62
63
64 # Beam3_1
65 p1 = [beam_dist_final+suspension_beam_width+small_beam_length+
      ↪ proof_mass_length,beam_dist_final+suspension_beam_width+
      ↪ small_beam_length+proof_mass_length - beam_to_mass -
      ↪ suspension_beam_width,beam_lower]
66 p2 = [small_beam_length,suspension_beam_width,beam_thickness]
67 beam3_1 = geom.add_box(p1,p2,char_length=c1*scale)
68
69 # Beam3_2
70 p1 = [beam_dist_final+suspension_beam_width+small_beam_length+
      ↪ proof_mass_length+small_beam_length,0,beam_lower]
71 p2 = [suspension_beam_width,suspension_beam_length,beam_thickness]
72 beam3_2 = geom.add_box(p1,p2,char_length=c1*scale)
73
74 # Beam3
75 beam3 = geom.boolean_union([beam3_1,beam3_2])
76
77
78 # Beam4_1
79 p1 = [beam_dist_final+suspension_beam_width+small_beam_length+beam_to_mass,
      ↪ beam_dist_final+suspension_beam_width+small_beam_length+
      ↪ proof_mass_length,beam_lower]
80 p2 = [suspension_beam_width,small_beam_length,beam_thickness]
81 beam4_1 = geom.add_box(p1,p2,char_length=c1*scale)
82
83 # Beam4_2
84 p1 = [beam_dist_final+suspension_beam_width+small_beam_length+beam_to_mass,
      ↪ beam_dist_final+suspension_beam_width+small_beam_length+
      ↪ proof_mass_length+small_beam_length,beam_lower]
85 p2 = [suspension_beam_length,suspension_beam_width,beam_thickness]
86 beam4_2 = geom.add_box(p1,p2,char_length=c1*scale)
87
88 # Beam 4
89 beam4 = geom.boolean_union([beam4_1,beam4_2])
90
91
92 #Complete Union
93 final = geom.boolean_union([beam1,proof_mass,beam2,beam3,beam4])
94
95 mesh = pg.generate_mesh(geom,gmsh_path="/home/ruiesteves/Documents/Tese/
      ↪ MechanicalModel/gmsh-4.5.2-Linux64/bin/gmsh") # Be sure to change the
      ↪ gmsh_path to the installed folder
96 meshio.write("accelerometer.xml",mesh)

```

Listing I.2: FEM displacement script

```

1  # MEMS accelerometer displacement simulation script
2  # @ruiesteves
3
4  # Imports
5  from __future__ import print_function
6  from dolfin import *
7
8  # Material constants
9  E = Constant(170e9)
10 nu = Constant(0.28)
11 rho = 2329
12 mu = E/2/(1+nu)
13 lmbda = E*nu/(1+nu)/(1-2*nu)
14
15 # Mesh
16 mesh = Mesh('accelerometer.xml')
17
18
19 def disp(suspension_beam_width,proof_mass_length):
20
21     # Constants
22     scale = 1e-6
23     suspension_beam_length = 3300*scale
24     beam_thickness = 69*scale
25     small_beam_length = 500*scale
26     proof_mass_thickness = 320*scale
27     beam_dist = 500*scale
28     beam_l = 122.5 * scale
29     beam_h = 177.5 * scale
30     beam_dist2 = beam_dist + suspension_beam_length
31     beam_dist3 = proof_mass_length + suspension_beam_width + small_beam_length
32     beam_dist_final = beam_dist2 - beam_dist3
33     beam_lower = (proof_mass_thickness - beam_thickness)/2
34     beam_to_mass = (beam_dist_final+suspension_beam_width+small_beam_length +
35         ↪ proof_mass_length) - suspension_beam_length
36     anchor_top = beam_dist_final+suspension_beam_width+small_beam_length+
37         ↪ beam_to_mass+suspension_beam_length
38     volume_PM = proof_mass_length**2 * proof_mass_thickness
39
40     # Strain operator
41     def eps(v):
42         return sym(grad(v))
43
44     # Stress tensor

```

---

```

43 def sigma(v):
44     return lmbda*tr(eps(v))*Identity(3) + 2.0*mu*eps(v)
45
46
47 # Boundary
48 def left(x,on_boundary):
49     return near(x[0],0.)
50
51 def bottom(x,on_boundary):
52     return near(x[1],0.)
53
54 def top(x,on_boundary):
55     return near(x[1],anchor_top)
56
57 def right(x,on_boundary):
58     return near(x[0],anchor_top)
59
60 def main():
61     rho_g = 9.8*(rho)
62     print("Volume:",volume_PM)
63     print("Force:",rho_g)
64     f = Constant((0.,0.,rho_g))
65     T = Constant((0,0,0))
66     V = VectorFunctionSpace(mesh,'Lagrange',degree=3)
67     du = TrialFunction(V)
68     u_ = TestFunction(V)
69     a = inner(sigma(du),eps(u_))*dx
70     l = dot(f,u_)*dx
71
72     bc = [DirichletBC(V, Constant((0.,0.,0.)),left),
73           DirichletBC(V, Constant((0.,0.,0.)),right),
74           DirichletBC(V, Constant((0.,0.,0.)),top),
75           DirichletBC(V, Constant((0.,0.,0.)),bottom)]
76     u = Function(V, name='Displacement')
77     solve(a == l, u, bc)
78     z_disp = u(beam_dist_final+suspension_beam_width+small_beam_length+
79                ↳ proof_mass_length/2,beam_dist_final+suspension_beam_width+
80                ↳ small_beam_length+proof_mass_length/2,proof_mass_thickness/2)
81
82     # Set up file for exporting results
83     file_results = XDMFFile("acc_displacement.xdmf")
84     file_results.parameters["flush_output"] = True
85     file_results.parameters["functions_share_mesh"] = True
86     file_results.write(u,0)

```

```

86     print(z_disp[2]*1e6,"um")
87     return z_disp[2]
88
89     return main()

```

Listing I.3: Modal analysis simulation script

```

1  # MEMS accelerometer modal analysis script
2  # @ruiesteves
3
4  # Imports
5  from fenics import *
6  import numpy as np
7
8  # Material constants
9  E = Constant(170e9)
10 nu = Constant(0.28)
11 rho = 2329
12 mu = E/2/(1+nu)
13 lmbda = E*nu/(1+nu)/(1-2*nu)
14
15 # Meshing
16 mesh = Mesh('accelerometer.xml')
17
18
19 def main(suspension_beam_width,proof_mass_length):
20
21     # Constants
22     cl = 175
23     proof_mass_cl = 150
24     scale = 1e-6
25     suspension_beam_length = 3300*scale
26     beam_thickness = 69*scale
27     small_beam_length = 500*scale
28     proof_mass_thickness = 320*scale
29     beam_dist = 500*scale
30     beam_l = 122.5 * scale
31     beam_h = 177.5 * scale
32     beam_dist2 = beam_dist + suspension_beam_length
33     beam_dist3 = proof_mass_length + suspension_beam_width + small_beam_length
34     beam_dist_final = beam_dist2 - beam_dist3
35     beam_lower = (proof_mass_thickness - beam_thickness)/2
36     beam_to_mass = (beam_dist_final+suspension_beam_width+small_beam_length +
37         ↪ proof_mass_length) - suspension_beam_length
38     anchor_top = beam_dist_final+suspension_beam_width+small_beam_length+
39         ↪ beam_to_mass+suspension_beam_length

```



---

```

38
39 # Functions
40 def eps(v):
41     return sym(grad(v))
42
43 def sigma(v):
44     return lambda*tr(eps(v))*Identity(3) + 2.0*mu*eps(v)
45
46 # Function Space
47 V = VectorFunctionSpace(mesh, 'Lagrange', degree=3)
48 u_ = TrialFunction(V)
49 du = TestFunction(V)
50
51 # Boundary
52 def left(x, on_boundary):
53     return near(x[0], 0.)
54
55 def bottom(x, on_boundary):
56     return near(x[1], 0.)
57
58 def top(x, on_boundary):
59     return near(x[1], anchor_top)
60
61 def right(x, on_boundary):
62     return near(x[0], anchor_top)
63
64 bc = [DirichletBC(V, Constant((0., 0., 0.)), left),
65       DirichletBC(V, Constant((0., 0., 0.)), right),
66       DirichletBC(V, Constant((0., 0., 0.)), top),
67       DirichletBC(V, Constant((0., 0., 0.)), bottom)]
68
69 # Matrices
70 k_form = inner(sigma(du), eps(u_))*dx
71 l_form = Constant(1.)*u_[0]*dx
72 K = PETScMatrix()
73 b = PETScVector()
74 assemble_system(k_form, l_form, bc, A_tensor=K, b_tensor=b)
75
76 m_form = rho*dot(du, u_)*dx
77 M = PETScMatrix()
78 assemble(m_form, tensor=M)
79
80 # Eigenvalues/Eigensolver
81 eigensolver = SLEPcEigenSolver(K, M)
82 eigensolver.parameters['problem_type'] = 'gen_hermitian'

```

```

83     #eigsolver.parameters['spectrum'] = 'smallest real'
84     eigsolver.parameters['spectral_transform'] = 'shift-and-invert'
85     eigsolver.parameters['spectral_shift'] = 0.
86     N_eig = 2
87     eigsolver.solve(N_eig)
88     #print (eigsolver.parameters.str(True))
89
90     # Export results
91     file_results = XDMFFile('acc_modal_analysis.xdmf')
92     file_results.parameters['flush_output'] = True
93     file_results.parameters['functions_share_mesh'] = True
94
95     r1,c1,rx1,cx1 = eigsolver.get_eigenpair(0)
96     u = Function(V)
97     u.vector()[:] = rx1
98     file_results.write(u,0)
99
100    # Extraction
101    for i in range(N_eig):
102        r,c,rx,cx = eigsolver.get_eigenpair(i)
103        freq = sqrt(r)/2/pi
104        print('Mode:',i,'_mode','Freq:',freq,'[Hz]')
105
106
107    freq_final = sqrt(r1)/2/pi
108    return freq_final

```

Listing I.4: Electronic domain simulation script

```

1  # MEMS accelerometer electrical domain simulation
2  # @ruiesteves
3
4  # Imports
5  import acc_disp
6
7
8
9  # Constants
10 e0 = 8.85e-12 # Permittivity of free space
11 er = 1 # Relative permittivity of dielectric, in this case air
12 small_gap = 22*scale # Distance between electrodes and proof mass
13
14
15 # Functions
16
17 def main(suspension_beam_width,proof_mass_length):

```

```

18     disp = acc_disp.disp(suspension_beam_width,proof_mass_length)
19     A = (proof_mass_length)**2
20     def top_capacitance():
21         C = (e0*er*A)/(small_gap + disp)
22         return C
23
24     def bot_capacitance():
25         C = (e0*er*A)/(small_gap - disp)
26         return C
27
28     def capacitance_total():
29         c_total = bot_capacitance() - top_capacitance()
30         print(c_total*1e15,"fF")
31         return c_total
32
33     def c2v():
34         v = 2 * capacitance_total() * 2.5 * (1/300e-15)
35         print("Output_voltage:",v*1e3,"mV")
36         return v
37
38     voltage = c2v()
39     return voltage

```

### Listing I.5: Damping calculation script

```

1  # MEMS accelerometer squeeze film damping calculation script
2  # @ruiesteves
3
4  import math
5
6  epsilon0 = 8.85e-12
7  scale = 1e-6
8  mu = 1.86e-5 # the mean viscosity of the medium
9  lamb = 0.067e-6 # mean free path
10 small_gap = 22*scale
11 thickness = 320*scale
12 rho = 2329
13
14 def q_factor(suspension_beam_width,proof_mass_length,sense_frequency):
15     A = proof_mass_length**2
16     mass_sense = A * thickness * rho
17     Kn = lamb/small_gap
18     mu_eff = mu/(1+9.638*Kn**1.159)
19     Pa = 101.3e3
20     c = 1
21     squeeze_number = (12*mu_eff*2*math.pi*L_sense**2)/(Pa*small_gap**2)

```

```

22     sum = 0
23     for m in range(1,10,2):
24         for n in (1,10,2):
25             sum = sum + (m**2 + c**2 * n**2)/((m*n)**2 * ((m**2 + c**2 * n**2)**2
26                 ↪ + (squeeze_number**2 / math.pi**4)))
27
28     F_damping = ((64*squeeze_number*Pa*A)/(math.pi**6 * small_gap)) * sum
29     c_sense = F_damping
30     q_factor = mass_sense * sense_frequency*2*math.pi / c_sense
31
32     return q_factor

```

Listing I.6: Genetic algorithm script

```

1  # Python Accelerometer GA
2  # @ruiesteves
3
4  # Imports
5  import acc_geo
6  import acc_disp
7  import acc_elec
8  import acc_modal
9  import acc_damping
10 import numpy as np
11 import math as math
12 import random as rand
13 import copy
14
15 # Initial parameters of the device to be optimized
16 scale = 1e-6
17 suspension_beam_width = 350*scale
18 proof_mass_length = 2400*scale
19
20 initial = [suspension_beam_width,proof_mass_length]
21
22 # Classes
23 class GA_device:
24
25     def __init__(self,id):
26         self.list_parameters = []
27         self.id = id
28
29     def calc_sensitivity(self):
30         list = self.list_parameters
31         self.sensitivity = acc_elec.main(list[0],list[1])
32

```

---

```

33     def calc_freq(self):
34         list = self.list_parameters
35         self.freq = acc_modal.main(list[0],list[1])
36
37     def calc_qfactor(self):
38         list = self.list_parameters
39         self.qfactor = acc_damping.q_factor(list[0],list[1],self.freq)
40
41     def calc_fom(self):
42         list = self.list_parameters
43         try:
44             acc_geo.build(list[0],list[1])
45             self.calc_sensitivity()
46             self.calc_freq()
47             self.calc_qfactor()
48             self.fom = self.freq * self.sensitivity * self.qfactor * (1/1000)
49         except:
50             print("Geometry_became_invalid_for_device",self.id)
51             self.fom = 0
52
53
54 class GA: # GA class, initiated with a list of devices, a list of mutation
55     ↪ chances and a list of mutation relative size
56
57     def __init__(self,list_devices,mutation_chance,mutation_size):
58         self.list_devices = list_devices # Must be a list of GA_devices
59         self.mutation_chance = mutation_chance # A list, with different (or not)
60         ↪ mutation chances for each parameter
61         self.mutation_size = mutation_size # Same as above, this time for
62         ↪ mutation_sizes (IMPORTANT to check)
63
64     def mutate(self,dev): # The mutation function, mutating the parameters
65         ↪ according to their mutation chance and size
66         le = len(dev.list_parameters)
67         for i in range(le):
68             if rand.uniform(0,1) < self.mutation_chance[i]:
69                 if rand.uniform(0,1) < 0.5:
70                     dev.list_parameters[i] = dev.list_parameters[i] + dev.
71                     ↪ list_parameters[i]*self.mutation_size[i]
72                 else:
73                     dev.list_parameters[i] = dev.list_parameters[i] - dev.
74                     ↪ list_parameters[i]*self.mutation_size[i]
75
76     def reproduce(self,top_25):
77         new_population = []

```

```

72
73     for dev in top_25: # Passing the best 25 devices to the next generation
74         new_population.append(dev)
75
76     for dev in top_25: # Copying and mutating the best 25 devices to the next
77         ↪ generation
78         new_dev = copy.deepcopy(dev)
79         self.mutate(new_dev)
80         new_population.append(new_dev)
81
82     for i in range(len(self.list_devices)//2): # Randomly mutating and
83         ↪ passing half of the population to the next generation
84         new_dev_r = copy.deepcopy(self.list_devices[i])
85         self.mutate(new_dev_r)
86         new_population.append(new_dev_r)
87
88     return new_population
89
90 def one_generation(self):
91
92     for dev in self.list_devices:
93         dev.calc_fom()
94
95     le = len(self.list_devices)
96     scores = [self.list_devices[i].fom for i in range(le)]
97     max = np.amax(scores)
98     print(scores)
99     print(max)
100
101     top_25_index = list(np.argsort(scores))[3*(le//4):le]
102     top_25 = [self.list_devices[i] for i in top_25_index][::-1]
103
104     self.list_devices = self.reproduce(top_25)
105
106
107
108
109 # Script
110 print("Genetic_algorithm_optimization_for_MEMS_accelerometer")
111 num_pop = int(input("Size_of_the_population:_"))
112 num_gen = int(input("Number_of_generations:_"))
113
114 initial_pop = []

```

---

```

115 for i in range(num_pop):
116     initial_pop.append(GA_device(i))
117     for par in range(len(initial)):
118         initial_pop[i].list_parameters.append(initial[par])
119     initial_pop[i].calc_fom()
120
121 init_ga = GA(initial_pop,[0.6,0.6],[0.13,0.0143])
122
123 for i in range(num_gen):
124     init_ga.one_generation()
125     for dev in init_ga.list_devices:
126         print("\n","For_Device_number",dev.id,":")
127         print(dev.sensitivity*1e3,"mV/g")
128         print(dev.freq,"Hz")
129         print(dev.qfactor,"Q-factor")
130         print(dev.fom,"FOM")
131
132 max_score = 0
133
134
135 for dev in init_ga.list_devices:
136     if dev.fom > max_score:
137         max_score = dev.fom
138
139 print("Maximum_FOM:",max_score)

```







## SOFTWARE IMPLEMENTATION ON MEMS

### GYROSCOPE

In the following listings, the program implementation for a MEMS gyroscope is displayed. The code makes it possible to obtain the displacement due to an actuation force or coriolis force via [FEM](#) - however, it is recommended to make use of the displacement equations for long optimization runs.

Listing II.1: Geometry building block

```

1  # MEMS Gyroscope 3D Geometry
2  # @ruiesteves
3
4  # Imports
5  import pygmsh as pg # geometry & meshing definition
6  import meshio # meshing export
7
8  # Helper functions
9  def mirror_quarter_helper(mirror_quarter,x_point):
10     dist = mirror_quarter - x_point
11     x_new = mirror_quarter + dist
12     return x_new
13
14  def mirror_half_helper(drive_frame_beam_h,y_point):
15     dist = drive_frame_beam_h - y_point
16     y_new = drive_frame_beam_h + dist
17     return y_new
18
19  # Functions
20  def build(serpentine_width,proof_mass_beam_w,proof_mass_beam_h,
21  proof_mass_w,proof_mass_h,sense_comb_finger_h):
22
23     # Constants
24     scale = 1e-6
25     cl = 80*scale
26     small_cl = 9*scale
27     thickness = 50*scale
28     small_gap = 3*scale

```

```
29     large_gap = 4*small_gap
30     drive_anchor_width = 124*scale
31     drive_anchor_height = 126*scale
32     drive_serpentine_connector_w = 21*scale
33     drive_serpentine_connector_h = 24*scale
34     drive_serpentine_beam_h = 194*scale
35     drive_serpentine_connector2_w = 17*scale
36     drive_serpentine_connector2_h = 21*scale
37     drive_serpentine_beam2_x = drive_anchor_width + drive_serpentine_connector_w
    ↪ + serpentine_width + drive_serpentine_connector2_w
38     drive_serpentine_connector3_w = 17*scale
39     drive_serpentine_connector3_h = 24*scale
40     drive_frame_beam_w = 56*scale
41     drive_frame_beam_h = 485*scale
42     drive_frame_connector_w = 72*scale
43     drive_frame_connector_h = 73*scale
44     drive_frame_serpent_beam_w = 171*scale
45     drive_frame_serpent_connector_x = drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w + drive_frame_serpent_beam_w -
    ↪ drive_serpentine_connector2_h
46     drive_frame_base_w = 309*scale
47     drive_frame_base_h = 41*scale
48     sense_comb_finger_dist = (small_gap + large_gap + sense_comb_finger_h)
49     proof_mass_fingers_pole_w = 15*scale
50     proof_mass_fingers_pole_h = (3*(sense_comb_finger_dist+sense_comb_finger_h))
51     sense_comb_finger_w = 243*scale
52     sense_comb_finger_num = 3
53     drive_comb_finger_w = 48*scale
54     drive_comb_finger_h = 9*scale
55     drive_comb_finger_dist = (small_gap + large_gap + drive_comb_finger_h)
56     drive_comb_finger_num = 8
57     mirror_quarter = drive_serpentine_beam2_x + serpentine_width +
    ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w + proof_mass_w
58     mirror_gyro = mirror_quarter*2 - drive_anchor_width/2
59     drive_coupling_beam_w = 118.5*scale
60     drive_coupling_beam_h = 21*scale
61     drive_coupling_dist = 42.75*scale
62     drive_coupling_beam_vert_w = 9*scale
63     drive_coupling_dist2 = 95*scale
64     drive_coupling_beam_vert_h = drive_coupling_dist2*2 + drive_coupling_beam_h
65     drive_coupling_connector_w = 15*scale
66     drive_coupling_connector_h = 12*scale
67
```

```

68  # Geometry build
69  geom = pg.opencascade.Geometry()
70
71  # Drive anchor
72  p1 = [0,0,0]
73  p2 = [drive_anchor_width,drive_anchor_height,thickness]
74  drive_anchor = geom.add_box(p1,p2,char_length=c1)
75
76  # Drive serpentine connector
77  p3 = [drive_anchor_width,0,0]
78  p4 = [drive_serpentine_connector_w,drive_serpentine_connector_h,thickness]
79  drive_serpentine_connector = geom.add_box(p3,p4,char_length=c1)
80
81  # Drive serpentine beam
82  p5 = [drive_anchor_width + drive_serpentine_connector_w,0,0]
83  p6 = [serpentine_width,drive_serpentine_beam_h,thickness]
84  drive_serpentine_beam = geom.add_box(p5,p6,char_length=c1)
85
86  # Drive serpentine connector 2
87  p7 = [drive_anchor_width + drive_serpentine_connector_w + serpentine_width,
      ↪ drive_serpentine_beam_h - drive_serpentine_connector2_h,0]
88  p8 = [drive_serpentine_connector2_w,drive_serpentine_connector2_h,thickness]
89  drive_serpentine_connector2 = geom.add_box(p7,p8,char_length=c1)
90
91  # Drive serpentine beam 2
92  p9 = [drive_serpentine_beam2_x,0,0]
93  p10 = [serpentine_width,drive_serpentine_beam_h,thickness]
94  drive_serpentine_beam2 = geom.add_box(p9,p10,char_length=c1)
95
96  # Drive serpentine connector 3
97  p11 = [drive_serpentine_beam2_x + serpentine_width,0,0]
98  p12 = [drive_serpentine_connector3_w,drive_serpentine_connector3_h,thickness
      ↪ ]
99  drive_serpentine_connector3 = geom.add_box(p11,p12,char_length=c1)
100
101  # Drive frame beam
102  p13 = [drive_serpentine_beam2_x + serpentine_width +
      ↪ drive_serpentine_connector3_w,0,0]
103  p14 = [drive_frame_beam_w,drive_frame_beam_h,thickness]
104  drive_frame_beam = geom.add_box(p13,p14,char_length=c1)
105
106  # Drive frame connector
107  p15 = [drive_serpentine_beam2_x + serpentine_width +
      ↪ drive_serpentine_connector3_w+drive_frame_beam_w,0,0]
108  p16 = [drive_frame_connector_w,drive_frame_connector_h,thickness]

```

```

109     drive_frame_connector = geom.add_box(p15,p16,char_length=c1)
110
111     # Drive frame serpent beam
112     p17 = [drive_serpentine_beam2_x + serpentine_width +
            ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
            ↪ drive_frame_connector_w,drive_frame_connector_h - serpentine_width,0]
113     p18 = [drive_frame_serpent_beam_w,serpentine_width,thickness]
114     drive_frame_serpent_beam = geom.add_box(p17,p18,char_length=c1)
115
116     # Drive frame serpent connector
117     p19 = [drive_frame_serpent_connector_x,drive_frame_connector_h,0]
118     p20 = [drive_serpentine_connector2_h,drive_serpentine_connector2_w,thickness
            ↪ ]
119     drive_frame_serpent_connector = geom.add_box(p19,p20,char_length=c1)
120
121     # Drive frame serpent beam 2
122     p21 = [drive_serpentine_beam2_x + serpentine_width +
            ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
            ↪ drive_frame_connector_w,drive_frame_connector_h +
            ↪ drive_serpentine_connector2_w,0]
123     p22 = [drive_frame_serpent_beam_w,serpentine_width,thickness]
124     drive_frame_serpent_beam2 = geom.add_box(p21,p22,char_length=c1)
125
126     # Drive frame base
127     p23 = [drive_serpentine_beam2_x + serpentine_width +
            ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
            ↪ drive_frame_connector_w,0,0]
128     p24 = [drive_frame_base_w,drive_frame_base_h,thickness]
129     drive_frame_base = geom.add_box(p23,p24,char_length=c1)
130
131     # Proof mass beam
132     p25 = [drive_serpentine_beam2_x + serpentine_width +
            ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
            ↪ drive_frame_connector_w - proof_mass_beam_w,drive_frame_connector_h +
            ↪ drive_serpentine_connector2_w,0]
133     p26 = [proof_mass_beam_w,proof_mass_beam_h,thickness]
134     proof_mass_beam = geom.add_box(p25,p26,char_length=c1)
135
136     # Proof mass
137     p27 = [drive_serpentine_beam2_x + serpentine_width +
            ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
            ↪ drive_frame_connector_w, drive_frame_connector_h +
            ↪ drive_serpentine_connector2_w + proof_mass_beam_h - proof_mass_h,0]
138     p28 = [proof_mass_w,proof_mass_h,thickness]
139     proof_mass = geom.add_box(p27,p28,char_length=c1)

```

```

140
141 # Proof mass fingers pole
142 p29 = [drive_serpentine_beam2_x + serpentine_width +
        ↳ drive_serpentine_connector3_w+drive_frame_beam_w +
        ↳ drive_frame_connector_w + proof_mass_w - proof_mass_fingers_pole_w,
143 drive_frame_connector_h + drive_serpentine_connector2_w + proof_mass_beam_h -
        ↳ proof_mass_h - proof_mass_fingers_pole_h,0]
144 p30 = [proof_mass_fingers_pole_w,proof_mass_fingers_pole_h,thickness]
145 proof_mass_fingers_pole = geom.add_box(p29,p30,char_length=c1)
146
147 # Sense comb finger array
148 sense_comb_finger_array = []
149 for i in range(sense_comb_finger_num):
150     p31 = [drive_serpentine_beam2_x + serpentine_width +
            ↳ drive_serpentine_connector3_w+drive_frame_beam_w +
            ↳ drive_frame_connector_w + proof_mass_w - proof_mass_fingers_pole_w
            ↳ - sense_comb_finger_w,
151 drive_frame_connector_h + drive_serpentine_connector2_w +
            ↳ proof_mass_beam_h - proof_mass_h - proof_mass_fingers_pole_h + (i)
            ↳ *(sense_comb_finger_h + sense_comb_finger_dist),0]
152 p32 = [sense_comb_finger_w,sense_comb_finger_h,thickness]
153 name = "".join(["sense_comb_finger",str(i)])
154 name = geom.add_box(p31,p32,char_length=c1)
155 sense_comb_finger_array.append(name)
156 sense_comb_finger_complete = geom.boolean_union(sense_comb_finger_array)
157
158 # Drive comb finger array
159 drive_comb_finger_array = []
160 for i in range(drive_comb_finger_num):
161     p33 = [drive_serpentine_beam2_x + serpentine_width +
            ↳ drive_serpentine_connector3_w - drive_comb_finger_w,
162 drive_frame_beam_h - drive_comb_finger_dist/2 - drive_comb_finger_h - i*(
            ↳ drive_comb_finger_h + drive_comb_finger_dist),0]
163 p34 = [drive_comb_finger_w,drive_comb_finger_h,thickness]
164 name = "".join(["drive_comb_finger",str(i)])
165 name = geom.add_box(p33,p34,char_length=c1)
166 drive_comb_finger_array.append(name)
167 drive_comb_finger_complete = geom.boolean_union(drive_comb_finger_array)
168
169
170 # Quarter union
171 print("1st union starts here")
172 quarter = geom.boolean_union([drive_anchor,drive_serpentine_connector,
        ↳ drive_serpentine_beam,

```

```

173     drive_serpentine_connector2,drive_serpentine_beam2,
        ↳ drive_serpentine_connector3,drive_frame_beam,
174     drive_frame_connector,drive_frame_serpent_beam,drive_frame_serpent_connector,
        ↳ drive_frame_serpent_beam2,
175     drive_frame_base,proof_mass_beam,proof_mass,proof_mass_fingers_pole,
        ↳ sense_comb_finger_complete,
176     drive_comb_finger_complete]))
177
178
179     # QUARTER MIRROR STARTS HERE
180     # Drive anchor
181     p35 = [mirror_quarter_helper(mirror_quarter,0),0,0]
182     print("ANCHOR:",p35)
183     p36 = [-drive_anchor_width,drive_anchor_height,thickness]
184     drive_anchorq = geom.add_box(p35,p36,char_length=c1)
185
186     # Drive serpentine connector
187     p37 = [mirror_quarter_helper(mirror_quarter,drive_anchor_width),0,0]
188     p38 = [-drive_serpentine_connector_w,drive_serpentine_connector_h,thickness]
189     drive_serpentine_connectorq = geom.add_box(p37,p38,char_length=c1)
190
191     # Drive serpentine beam
192     p39 = [mirror_quarter_helper(mirror_quarter,drive_anchor_width +
        ↳ drive_serpentine_connector_w),0,0]
193     p40 = [-serpentine_width,drive_serpentine_beam_h,thickness]
194     drive_serpentine_beamq = geom.add_box(p39,p40,char_length=c1)
195
196     # Drive serpentine connector 2
197     p41 = [mirror_quarter_helper(mirror_quarter,drive_anchor_width +
        ↳ drive_serpentine_connector_w + serpentine_width),
        ↳ drive_serpentine_beam_h - drive_serpentine_connector2_h,0]
198     p42 = [-drive_serpentine_connector2_w,drive_serpentine_connector2_h,
        ↳ thickness]
199     drive_serpentine_connector2q = geom.add_box(p41,p42,char_length=c1)
200
201     # Drive serpentine beam 2
202     p9 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x),0,0]
203     p10 = [-serpentine_width,drive_serpentine_beam_h,thickness]
204     drive_serpentine_beam2q = geom.add_box(p9,p10,char_length=c1)
205
206     # Drive serpentine connector 3
207     p11 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
        ↳ serpentine_width),0,0]
208     p12 = [-drive_serpentine_connector3_w,drive_serpentine_connector3_h,
        ↳ thickness]

```

```

209 drive_serpentine_connector3q = geom.add_box(p11,p12,char_length=c1)
210
211 # Drive frame beam
212 p13 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w),0,0]
213 p14 = [-drive_frame_beam_w,drive_frame_beam_h,thickness]
214 drive_frame_beamq = geom.add_box(p13,p14,char_length=c1)
215
216 # Drive frame connector
217 p15 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w)
    ↪ ,0,0]
218 p16 = [-drive_frame_connector_w,drive_frame_connector_h,thickness]
219 drive_frame_connectorq = geom.add_box(p15,p16,char_length=c1)
220
221 # Drive frame serpent beam
222 p17 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w),drive_frame_connector_h - serpentine_width,0]
223 p18 = [-drive_frame_serpent_beam_w,serpentine_width,thickness]
224 drive_frame_serpent_beamq = geom.add_box(p17,p18,char_length=c1)
225
226 # Drive frame serpent connector
227 p19 = [mirror_quarter_helper(mirror_quarter,drive_frame_serpent_connector_x),
    ↪ drive_frame_connector_h,0]
228 p20 = [-drive_serpentine_connector2_h,drive_serpentine_connector2_w,
    ↪ thickness]
229 drive_frame_serpent_connectorq = geom.add_box(p19,p20,char_length=c1)
230
231 # Drive frame serpent beam 2
232 p21 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w),drive_frame_connector_h +
    ↪ drive_serpentine_connector2_w,0]
233 p22 = [-drive_frame_serpent_beam_w,serpentine_width,thickness]
234 drive_frame_serpent_beam2q = geom.add_box(p21,p22,char_length=c1)
235
236 # Drive frame base
237 p23 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w),0,0]
238 p24 = [-drive_frame_base_w,drive_frame_base_h,thickness]
239 drive_frame_baseq = geom.add_box(p23,p24,char_length=c1)
240
241 # Proof mass beam

```

```

242 p25 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w - proof_mass_beam_w),drive_frame_connector_h +
    ↳ drive_serpentine_connector2_w,0]
243 p26 = [-proof_mass_beam_w,proof_mass_beam_h,thickness]
244 proof_mass_beamq = geom.add_box(p25,p26,char_length=c1)
245
246 # Proof mass
247 p27 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w), drive_frame_connector_h +
    ↳ drive_serpentine_connector2_w + proof_mass_beam_h - proof_mass_h,0]
248 p28 = [-proof_mass_w,proof_mass_h,thickness]
249 proof_massq = geom.add_box(p27,p28,char_length=c1)
250
251 # Proof mass fingers pole
252 p29 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + proof_mass_w - proof_mass_fingers_pole_w),
253 drive_frame_connector_h + drive_serpentine_connector2_w + proof_mass_beam_h -
    ↳ proof_mass_h - proof_mass_fingers_pole_h,0]
254 p30 = [-proof_mass_fingers_pole_w,proof_mass_fingers_pole_h,thickness]
255 proof_mass_fingers_poleq = geom.add_box(p29,p30,char_length=c1)
256
257 # Sense comb finger array
258 sense_comb_finger_array = []
259 for i in range(sense_comb_finger_num):
260     p31 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+
    ↳ drive_frame_beam_w + drive_frame_connector_w + proof_mass_w -
    ↳ proof_mass_fingers_pole_w - sense_comb_finger_w),
261 drive_frame_connector_h + drive_serpentine_connector2_w +
    ↳ proof_mass_beam_h - proof_mass_h - proof_mass_fingers_pole_h + (i)
    ↳ *(sense_comb_finger_h + sense_comb_finger_dist),0]
262 p32 = [-sense_comb_finger_w,sense_comb_finger_h,thickness]
263 name = "".join(["sense_comb_finger",str(i)])
264 name = geom.add_box(p31,p32,char_length=c1)
265 sense_comb_finger_array.append(name)
266 sense_comb_finger_completeq = geom.boolean_union(sense_comb_finger_array)
267
268 # Drive comb finger array
269 drive_comb_finger_array = []
270 for i in range(drive_comb_finger_num):

```



```

271     p33 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w -
    ↪ drive_comb_finger_w),
272     drive_frame_beam_h - drive_comb_finger_dist/2 - drive_comb_finger_h - i*(
    ↪ drive_comb_finger_h + drive_comb_finger_dist),0]
273     p34 = [-drive_comb_finger_w,drive_comb_finger_h,thickness]
274     name = "".join(["drive_comb_finger",str(i)])
275     name = geom.add_box(p33,p34,char_length=c1)
276     drive_comb_finger_array.append(name)
277     drive_comb_finger_completeq = geom.boolean_union(drive_comb_finger_array)
278
279     print("2nd Union starts here")
280     # Quarter union
281     quarter_right = geom.boolean_union([drive_anchorq,
    ↪ drive_serpentine_connectorq,drive_serpentine_beamq,
282     drive_serpentine_connector2q,drive_serpentine_beam2q,
    ↪ drive_serpentine_connector3q,drive_frame_beamq,
283     drive_frame_connectorq,drive_frame_serpent_beamq,
    ↪ drive_frame_serpent_connectorq,drive_frame_serpent_beam2q,
284     drive_frame_baseq,proof_mass_beamq,proof_massq,proof_mass_fingers_poleq,
    ↪ sense_comb_finger_completeq,
285     drive_comb_finger_completeq])
286
287
288
289     # HALF MIRRORING STARTS FROM HERE
290     # Drive anchor
291     p1 = [0,mirror_half_helper(drive_frame_beam_h,0),0]
292     p2 = [drive_anchor_width,-drive_anchor_height,thickness]
293     drive_anchorh = geom.add_box(p1,p2,char_length=c1)
294
295     # Drive serpentine connector
296     p3 = [drive_anchor_width,mirror_half_helper(drive_frame_beam_h,0),0]
297     p4 = [drive_serpentine_connector_w,-drive_serpentine_connector_h,thickness]
298     drive_serpentine_connectorh = geom.add_box(p3,p4,char_length=c1)
299
300     # Drive serpentine beam
301     p5 = [drive_anchor_width + drive_serpentine_connector_w,mirror_half_helper(
    ↪ drive_frame_beam_h,0),0]
302     p6 = [serpentine_width,-drive_serpentine_beam_h,thickness]
303     drive_serpentine_beamh = geom.add_box(p5,p6,char_length=c1)
304
305     # Drive serpentine connector 2

```

```

306     p7 = [drive_anchor_width + drive_serpentine_connector_w + serpentine_width,
           ↪ mirror_half_helper(drive_frame_beam_h,drive_serpentine_beam_h -
           ↪ drive_serpentine_connector2_h),0]
307     p8 = [drive_serpentine_connector2_w,-drive_serpentine_connector2_h,thickness
           ↪ ]
308     drive_serpentine_connector2h = geom.add_box(p7,p8,char_length=c1)
309
310     # Drive serpentine beam 2
311     p9 = [drive_serpentine_beam2_x,mirror_half_helper(drive_frame_beam_h,0),0]
312     p10 = [serpentine_width,-drive_serpentine_beam_h,thickness]
313     drive_serpentine_beam2h = geom.add_box(p9,p10,char_length=c1)
314
315     # Drive serpentine connector 3
316     p11 = [drive_serpentine_beam2_x + serpentine_width,mirror_half_helper(
           ↪ drive_frame_beam_h,0),0]
317     p12 = [drive_serpentine_connector3_w,-drive_serpentine_connector3_h,
           ↪ thickness]
318     drive_serpentine_connector3h = geom.add_box(p11,p12,char_length=c1)
319
320     # Drive frame beam
321     p13 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w,mirror_half_helper(drive_frame_beam_h,0)
           ↪ ,0]
322     p14 = [drive_frame_beam_w,-drive_frame_beam_h,thickness]
323     drive_frame_beamh = geom.add_box(p13,p14,char_length=c1)
324
325     # Drive frame connector
326     p15 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w+drive_frame_beam_w,mirror_half_helper(
           ↪ drive_frame_beam_h,0),0]
327     p16 = [drive_frame_connector_w,-drive_frame_connector_h,thickness]
328     drive_frame_connectorh = geom.add_box(p15,p16,char_length=c1)
329
330     # Drive frame serpent beam
331     p17 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
           ↪ drive_frame_connector_w,mirror_half_helper(drive_frame_beam_h,
           ↪ drive_frame_connector_h - serpentine_width),0]
332     p18 = [drive_frame_serpent_beam_w,-serpentine_width,thickness]
333     drive_frame_serpent_beamh = geom.add_box(p17,p18,char_length=c1)
334
335     # Drive frame serpent connector
336     p19 = [drive_frame_serpent_connector_x,mirror_half_helper(drive_frame_beam_h,
           ↪ drive_frame_connector_h),0]

```

```

337     p20 = [drive_serpentine_connector2_h,-drive_serpentine_connector2_w,
           ↪ thickness]
338     drive_frame_serpent_connectorh = geom.add_box(p19,p20,char_length=c1)
339
340     # Drive frame serpent beam 2
341     p21 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
           ↪ drive_frame_connector_w,mirror_half_helper(drive_frame_beam_h,
           ↪ drive_frame_connector_h + drive_serpentine_connector2_w),0]
342     p22 = [drive_frame_serpent_beam_w,-serpentine_width,thickness]
343     drive_frame_serpent_beam2h = geom.add_box(p21,p22,char_length=c1)
344
345     # Drive frame base
346     p23 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
           ↪ drive_frame_connector_w,mirror_half_helper(drive_frame_beam_h,0),0]
347     p24 = [drive_frame_base_w,-drive_frame_base_h,thickness]
348     drive_frame_baseh = geom.add_box(p23,p24,char_length=c1)
349
350     # Proof mass beam
351     p25 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
           ↪ drive_frame_connector_w - proof_mass_beam_w,mirror_half_helper(
           ↪ drive_frame_beam_h,drive_frame_connector_h +
           ↪ drive_serpentine_connector2_w),0]
352     p26 = [proof_mass_beam_w,-proof_mass_beam_h,thickness]
353     proof_mass_beamh = geom.add_box(p25,p26,char_length=c1)
354
355     # Proof mass
356     p27 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
           ↪ drive_frame_connector_w, mirror_half_helper(drive_frame_beam_h,
           ↪ drive_frame_connector_h + drive_serpentine_connector2_w +
           ↪ proof_mass_beam_h - proof_mass_h),0]
357     p28 = [proof_mass_w,-proof_mass_h,thickness]
358     proof_massh = geom.add_box(p27,p28,char_length=c1)
359
360     # Proof mass fingers pole
361     p29 = [drive_serpentine_beam2_x + serpentine_width +
           ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
           ↪ drive_frame_connector_w + proof_mass_w - proof_mass_fingers_pole_w,
362     mirror_half_helper(drive_frame_beam_h,drive_frame_connector_h +
           ↪ drive_serpentine_connector2_w + proof_mass_beam_h - proof_mass_h -
           ↪ proof_mass_fingers_pole_h),0]
363     p30 = [proof_mass_fingers_pole_w,-proof_mass_fingers_pole_h,thickness]

```

```

364 proof_mass_fingers_poleh = geom.add_box(p29,p30,char_length=c1)
365
366 # Sense comb finger array
367 sense_comb_finger_array = []
368 for i in range(sense_comb_finger_num):
369     p31 = [drive_serpentine_beam2_x + serpentine_width +
370             ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
371             ↪ drive_frame_connector_w + proof_mass_w - proof_mass_fingers_pole_w
372             ↪ - sense_comb_finger_w,
373             mirror_half_helper(drive_frame_beam_h,drive_frame_connector_h +
374                                 ↪ drive_serpentine_connector2_w + proof_mass_beam_h - proof_mass_h -
375                                 ↪ proof_mass_fingers_pole_h + (i)*(sense_comb_finger_h +
376                                 ↪ sense_comb_finger_dist)),0]
377     p32 = [sense_comb_finger_w,-sense_comb_finger_h,thickness]
378     name = "".join(["sense_comb_finger",str(i)])
379     name = geom.add_box(p31,p32,char_length=c1)
380     sense_comb_finger_array.append(name)
381 sense_comb_finger_completeh = geom.boolean_union(sense_comb_finger_array)
382
383 # Drive comb finger array
384 drive_comb_finger_array = []
385 for i in range(drive_comb_finger_num):
386     p33 = [drive_serpentine_beam2_x + serpentine_width +
387             ↪ drive_serpentine_connector3_w - drive_comb_finger_w,
388             mirror_half_helper(drive_frame_beam_h,drive_frame_beam_h -
389                                 ↪ drive_comb_finger_dist/2 - drive_comb_finger_h - i*(
390                                 ↪ drive_comb_finger_h + drive_comb_finger_dist)),0]
391     p34 = [drive_comb_finger_w,-drive_comb_finger_h,thickness]
392     name = "".join(["drive_comb_finger",str(i)])
393     name = geom.add_box(p33,p34,char_length=c1)
394     drive_comb_finger_array.append(name)
395 drive_comb_finger_completeh = geom.boolean_union(drive_comb_finger_array)
396
397 print("3rd Union starts here")
398 # Quarter union
399 quarter_h = geom.boolean_union([drive_anchorh,drive_serpentine_connectorh,
400                                 ↪ drive_serpentine_beamh,
401                                 drive_serpentine_connector2h,drive_serpentine_beam2h,
402                                 ↪ drive_serpentine_connector3h,drive_frame_beamh,
403                                 drive_frame_connectorh,drive_frame_serpent_beamh,
404                                 ↪ drive_frame_serpent_connectorh,drive_frame_serpent_beam2h,
405                                 drive_frame_baseh,proof_mass_beamh,proof_masssh,proof_mass_fingers_poleh,
406                                 ↪ sense_comb_finger_completeh,
407                                 drive_comb_finger_completeh])

```

```

396
397
398 # QUARTER MIRROR STARTS HERE
399 # Drive anchor
400 p35 = [mirror_quarter_helper(mirror_quarter,0),mirror_half_helper(
    ↳ drive_frame_beam_h,0),0]
401 p36 = [-drive_anchor_width,-drive_anchor_height,thickness]
402 drive_anchorqh = geom.add_box(p35,p36,char_length=c1)
403
404 # Drive serpentine connector
405 p37 = [mirror_quarter_helper(mirror_quarter,drive_anchor_width),
    ↳ mirror_half_helper(drive_frame_beam_h,0),0]
406 p38 = [-drive_serpentine_connector_w,-drive_serpentine_connector_h,thickness
    ↳ ]
407 drive_serpentine_connectorqh = geom.add_box(p37,p38,char_length=c1)
408
409 # Drive serpentine beam
410 p39 = [mirror_quarter_helper(mirror_quarter,drive_anchor_width +
    ↳ drive_serpentine_connector_w),mirror_half_helper(drive_frame_beam_h,0)
    ↳ ,0]
411 p40 = [-serpentine_width,-drive_serpentine_beam_h,thickness]
412 drive_serpentine_beamqh = geom.add_box(p39,p40,char_length=c1)
413
414 # Drive serpentine connector 2
415 p41 = [mirror_quarter_helper(mirror_quarter,drive_anchor_width +
    ↳ drive_serpentine_connector_w + serpentine_width),mirror_half_helper(
    ↳ drive_frame_beam_h,drive_serpentine_beam_h -
    ↳ drive_serpentine_connector2_h),0]
416 p42 = [-drive_serpentine_connector2_w,-drive_serpentine_connector2_h,
    ↳ thickness]
417 drive_serpentine_connector2qh = geom.add_box(p41,p42,char_length=c1)
418
419 # Drive serpentine beam 2
420 p9 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x),
    ↳ mirror_half_helper(drive_frame_beam_h,0),0]
421 p10 = [-serpentine_width,-drive_serpentine_beam_h,thickness]
422 drive_serpentine_beam2qh = geom.add_box(p9,p10,char_length=c1)
423
424 # Drive serpentine connector 3
425 p11 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width),mirror_half_helper(drive_frame_beam_h,0),0]
426 p12 = [-drive_serpentine_connector3_w,-drive_serpentine_connector3_h,
    ↳ thickness]
427 drive_serpentine_connector3qh = geom.add_box(p11,p12,char_length=c1)
428

```

```

429  # Drive frame beam
430  p13 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w),mirror_half_helper(
    ↪ drive_frame_beam_h,0),0]
431  p14 = [-drive_frame_beam_w,-drive_frame_beam_h,thickness]
432  drive_frame_beamqh = geom.add_box(p13,p14,char_length=c1)
433
434  # Drive frame connector
435  p15 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w),
    ↪ mirror_half_helper(drive_frame_beam_h,0),0]
436  p16 = [-drive_frame_connector_w,-drive_frame_connector_h,thickness]
437  drive_frame_connectorqh = geom.add_box(p15,p16,char_length=c1)
438
439  # Drive frame serpent beam
440  p17 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w),mirror_half_helper(drive_frame_beam_h,
    ↪ drive_frame_connector_h - serpentine_width),0]
441  p18 = [-drive_frame_serpent_beam_w,-serpentine_width,thickness]
442  drive_frame_serpent_beamqh = geom.add_box(p17,p18,char_length=c1)
443
444  # Drive frame serpent connector
445  p19 = [mirror_quarter_helper(mirror_quarter,drive_frame_serpent_connector_x),
    ↪ mirror_half_helper(drive_frame_beam_h,drive_frame_connector_h),0]
446  p20 = [-drive_serpentine_connector2_h,-drive_serpentine_connector2_w,
    ↪ thickness]
447  drive_frame_serpent_connectorqh = geom.add_box(p19,p20,char_length=c1)
448
449  # Drive frame serpent beam 2
450  p21 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w),mirror_half_helper(drive_frame_beam_h,
    ↪ drive_frame_connector_h + drive_serpentine_connector2_w),0]
451  p22 = [-drive_frame_serpent_beam_w,-serpentine_width,thickness]
452  drive_frame_serpent_beam2qh = geom.add_box(p21,p22,char_length=c1)
453
454  # Drive frame base
455  p23 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↪ drive_frame_connector_w),mirror_half_helper(drive_frame_beam_h,0),0]
456  p24 = [-drive_frame_base_w,-drive_frame_base_h,thickness]
457  drive_frame_baseqh = geom.add_box(p23,p24,char_length=c1)
458
459  # Proof mass beam

```

```

460 p25 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w - proof_mass_beam_w),mirror_half_helper(
    ↳ drive_frame_connector_h + drive_serpentine_connector2_w),0]
461 p26 = [-proof_mass_beam_w,-proof_mass_beam_h,thickness]
462 proof_mass_beamqh = geom.add_box(p25,p26,char_length=c1)
463
464 # Proof mass
465 p27 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w), mirror_half_helper(drive_frame_beam_h,
    ↳ drive_frame_connector_h + drive_serpentine_connector2_w +
    ↳ proof_mass_beam_h - proof_mass_h),0]
466 p28 = [-proof_mass_w,-proof_mass_h,thickness]
467 proof_massqh = geom.add_box(p27,p28,char_length=c1)
468
469 # Proof mass fingers pole
470 p29 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + proof_mass_w - proof_mass_fingers_pole_w),
471 mirror_half_helper(drive_frame_beam_h,drive_frame_connector_h +
    ↳ drive_serpentine_connector2_w + proof_mass_beam_h - proof_mass_h -
    ↳ proof_mass_fingers_pole_h),0]
472 p30 = [-proof_mass_fingers_pole_w,-proof_mass_fingers_pole_h,thickness]
473 proof_mass_fingers_poleqh = geom.add_box(p29,p30,char_length=c1)
474
475 # Sense comb finger array
476 sense_comb_finger_array = []
477 for i in range(sense_comb_finger_num):
478     p31 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+
    ↳ drive_frame_beam_w + drive_frame_connector_w + proof_mass_w -
    ↳ proof_mass_fingers_pole_w - sense_comb_finger_w),
479 mirror_half_helper(drive_frame_beam_h,drive_frame_connector_h +
    ↳ drive_serpentine_connector2_w + proof_mass_beam_h - proof_mass_h -
    ↳ proof_mass_fingers_pole_h + (i)*(sense_comb_finger_h +
    ↳ sense_comb_finger_dist)),0]
480 p32 = [-sense_comb_finger_w,-sense_comb_finger_h,thickness]
481 name = "".join(["sense_comb_finger",str(i)])
482 name = geom.add_box(p31,p32,char_length=c1)
483 sense_comb_finger_array.append(name)
484 sense_comb_finger_completeqh = geom.boolean_union(sense_comb_finger_array)
485
486 # Drive comb finger array
487 drive_comb_finger_array = []

```

```

488     for i in range(drive_comb_finger_num):
489         p33 = [mirror_quarter_helper(mirror_quarter,drive_serpentine_beam2_x +
            ↳ serpentine_width + drive_serpentine_connector3_w -
            ↳ drive_comb_finger_w),
490         mirror_half_helper(drive_frame_beam_h,drive_frame_beam_h -
            ↳ drive_comb_finger_dist/2 - drive_comb_finger_h - i*(
            ↳ drive_comb_finger_h + drive_comb_finger_dist)),0]
491         p34 = [-drive_comb_finger_w,-drive_comb_finger_h,thickness]
492         name = "".join(["drive_comb_finger",str(i)])
493         name = geom.add_box(p33,p34,char_length=cl)
494         drive_comb_finger_array.append(name)
495     drive_comb_finger_completeqh = geom.boolean_union(drive_comb_finger_array)
496
497     print("4th_union_starts_here")
498     # Quarter union
499     quarter_qh = geom.boolean_union([drive_anchorqh,drive_serpentine_connectorqh,
            ↳ drive_serpentine_beamqh,
500     drive_serpentine_connector2qh,drive_serpentine_beam2qh,
            ↳ drive_serpentine_connector3qh,drive_frame_beamqh,
501     drive_frame_connectorqh,drive_frame_serpent_beamqh,
            ↳ drive_frame_serpent_connectorqh,drive_frame_serpent_beam2qh,
502     drive_frame_baseqh,proof_mass_beamqh,proof_massqh,proof_mass_fingers_poleqh,
            ↳ sense_comb_finger_completeqh,
503     drive_comb_finger_completeqh])
504
505
506
507
508
509     print("Final_union_starts_here")
510     # Complete union
511     complete = geom.boolean_union([quarter,quarter_right,quarter_h,quarter_qh])
512
513
514
515
516
517     mesh = pg.generate_mesh(geom,gmsh_path="/home/ruiesteves/Documents/Tese/
            ↳ MechanicalModel/gmsh-4.5.2-Linux64/bin/gmsh")
518     meshio.write("gyroscope.xml",mesh)
519     #meshio.write("antiphase_geo.mesh",mesh)
520
521     return mesh

```

Listing II.2: Displacement simulation script



---

```

1  # MEMS Gyroscope displacement simulation script
2  # @ruiesteves
3
4  # Imports
5  from __future__ import print_function
6  from dolfin import *
7  import math
8  import gyro_elec
9  import gyro_damping
10
11 # Helper functions
12 def mirror_quarter_helper(mirror_quarter,x_point):
13     dist = mirror_quarter - x_point
14     x_new = mirror_quarter + dist
15     return x_new
16
17 def mirror_half_helper(drive_frame_beam_h,y_point):
18     dist = drive_frame_beam_h - y_point
19     y_new = drive_frame_beam_h + dist
20     return y_new
21
22
23 # Constants
24 E = Constant(170e9)
25 nu = Constant(0.28)
26 rho = 2329
27 mu = E/2/(1+nu)
28 lmbda = E*nu/(1+nu)/(1-2*nu)
29
30
31 # The user can choose between the two ways of calculating displacement: FEM
32     ↪ simulation or equations. For long optimization runs, the equations
33     ↪ approach is preferred.
34 def disp_equations(serpentine_width,proof_mass_beam_w,proof_mass_beam_h,
35     ↪ proof_mass_w,proof_mass_h,sense_comb_finger_h,q_factor_sense,
36     ↪ q_factor_drive,drive_frequency,sense_frequency):
37
38     # Constants
39     scale = 1e-6
40     cl = 80*scale
41     small_cl = 9*scale
42     thickness = 50*scale
43     small_gap = 3*scale
44     large_gap = 4*small_gap
45     drive_anchor_width = 124*scale

```

```

42     drive_anchor_height = 126*scale
43     drive_serpentine_connector_w = 21*scale
44     drive_serpentine_connector_h = 24*scale
45     drive_serpentine_beam_h = 194*scale
46     drive_serpentine_connector2_w = 17*scale
47     drive_serpentine_connector2_h = 21*scale
48     drive_serpentine_beam2_x = drive_anchor_width + drive_serpentine_connector_w
      ↪ + serpentine_width + drive_serpentine_connector2_w
49     drive_serpentine_connector3_w = 17*scale
50     drive_serpentine_connector3_h = 24*scale
51     drive_frame_beam_w = 56*scale
52     drive_frame_beam_h = 485*scale
53     drive_frame_connector_w = 72*scale
54     drive_frame_connector_h = 73*scale
55     drive_frame_serpent_beam_w = 171*scale
56     drive_frame_serpent_connector_x = drive_serpentine_beam2_x +
      ↪ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
      ↪ drive_frame_connector_w + drive_frame_serpent_beam_w -
      ↪ drive_serpentine_connector2_h
57     drive_frame_base_w = 309*scale
58     drive_frame_base_h = 41*scale
59     sense_comb_finger_dist = (small_gap + large_gap + sense_comb_finger_h)
60     proof_mass_fingers_pole_w = 15*scale
61     proof_mass_fingers_pole_h = (3*(sense_comb_finger_dist+sense_comb_finger_h))
62     sense_comb_finger_w = 243*scale
63     sense_comb_finger_num = 3
64     drive_comb_finger_w = 48*scale
65     drive_comb_finger_h = 9*scale
66     drive_comb_finger_dist = (small_gap + large_gap + drive_comb_finger_h)
67     drive_comb_finger_num = 8
68     mirror_quarter = drive_serpentine_beam2_x + serpentine_width +
      ↪ drive_serpentine_connector3_w+drive_frame_beam_w +
      ↪ drive_frame_connector_w + proof_mass_w
69     mirror_gyro = mirror_quarter*2 - drive_anchor_width/2
70     drive_coupling_beam_w = 118.5*scale
71     drive_coupling_beam_h = 21*scale
72     drive_coupling_dist = 42.75*scale
73     drive_coupling_beam_vert_w = 9*scale
74     drive_coupling_dist2 = 95*scale
75     drive_coupling_beam_vert_h = drive_coupling_dist2*2 + drive_coupling_beam_h
76     drive_coupling_connector_w = 15*scale
77     drive_coupling_connector_h = 12*scale
78
79     Volume = ((drive_anchor_height*drive_anchor_width)*4 + (
      ↪ drive_serpentine_connector_h*drive_serpentine_connector_w)*4

```

```

80 + (serpentine_width*drive_serpentine_beam_h)*8 + (
      ↳ drive_serpentine_connector2_h*drive_serpentine_connector2_w)*8 +
81 (drive_serpentine_connector3_h*drive_serpentine_connector3_w)*4 + (
      ↳ drive_frame_beam_w*drive_frame_beam_h)*4 +
82 (drive_frame_connector_h*drive_frame_connector_w)*4 + (
      ↳ drive_frame_serpent_beam_w*serpentine_width)*8 +
83 (drive_frame_base_w*drive_frame_base_h)*4 + (proof_mass_beam_w*
      ↳ proof_mass_beam_h)*4 +
84 (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
      ↳ proof_mass_fingers_pole_h)*4 +
85 (sense_comb_finger_h*sense_comb_finger_w)*12 + (drive_comb_finger_h*
      ↳ drive_comb_finger_w)*32)*thickness
86
87 Volume_proof_mass = ((proof_mass_beam_w*proof_mass_beam_h)*4 +
88 (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
      ↳ proof_mass_fingers_pole_h)*4 +
89 (sense_comb_finger_h*sense_comb_finger_w)*12)*thickness
90
91 Volume_drive_frame = ((drive_frame_beam_w*drive_frame_beam_h)*4 + (
      ↳ drive_frame_connector_w*drive_frame_connector_h)*4 +
92 (drive_frame_serpent_beam_w*serpentine_width)*8 + (
      ↳ drive_serpentine_connector2_w*drive_serpentine_connector2_h)*4 +
93 (drive_frame_base_h*drive_frame_base_w)*4)*thickness
94
95 Volume_drive = Volume_proof_mass + Volume_drive_frame
96
97 # Constants
98 epsilon0 = 8.85e-12
99 L = 18*scale
100 Vdc = 8
101 Vac = 4
102 drive_frequency, sense_frequency = gyro_modal.main()
103 mu = 1.86e-5
104 lamb = 0.067e-6
105
106 def drive_amplitude(drive_frequency,q_factor):
107     drive_mass = Volume_drive*rho
108     kd = (drive_mass * (drive_frequency*2*math.pi)**2)
109     f_actuation = 2*epsilon0*L*thickness*drive_comb_finger_num*2*Vdc*Vac*(1/(
      ↳ small_gap**2))
110     X0 = q_factor * f_actuation / (drive_mass * (drive_frequency*2*math.pi)
      ↳ **2)
111     return X0
112
113 def coriolis_force(angular_rate,drive_frequency):

```

```

114     mass_coriolis = Volume_drive*rho
115     X0 = drive_amplitude()
116     F_coriolis = -2*mass_coriolis*angular_rate*X0*drive_frequency*2*math.pi
117     return F_coriolis
118
119
120     def sense_disp(angular_rate,Q_factor,q_factor_drive,drive_frequency,
121         ↪ sense_frequency):
122         Y0 = angular_rate * ((Volume_drive*rho) * drive_frequency*2*math.pi) *
123             ↪ (1/(Volume_proof_mass*rho * (sense_frequency*2*math.pi)**2)) * 2 *
124             ↪ drive_amplitude(drive_frequency,q_factor_drive) * (1/math.sqrt
125             ↪ ((1-((drive_frequency*2*math.pi)/(sense_frequency*2*math.pi))**2)
126             ↪ **2) + (1/Q_factor * ((drive_frequency*2*math.pi)/(sense_frequency
127             ↪ *2*math.pi))**2)
128         return Y0
129
130     return sense_disp(1,q_factor_sense,q_factor_drive,drive_frequency,
131         ↪ sense_frequency)
132
133
134     # Mesh
135     mesh = Mesh('gyroscope.xml')
136
137     def disp_fem(force,serpentine_width,proof_mass_beam_w,proof_mass_beam_h,
138     proof_mass_w,proof_mass_h,sense_comb_finger_h):
139
140         scale = 1e-6
141         cl = 80*scale
142         small_cl = 9*scale
143         thickness = 50*scale
144         small_gap = 3*scale
145         large_gap = 4*small_gap
146         drive_anchor_width = 124*scale
147         drive_anchor_height = 126*scale
148         drive_serpentine_connector_w = 21*scale
149         drive_serpentine_connector_h = 24*scale
150         drive_serpentine_beam_h = 194*scale
151         drive_serpentine_connector2_w = 17*scale
152         drive_serpentine_connector2_h = 21*scale
153         drive_serpentine_beam2_x = drive_anchor_width + drive_serpentine_connector_w
154             ↪ + serpentine_width + drive_serpentine_connector2_w
155         drive_serpentine_connector3_w = 17*scale
156         drive_serpentine_connector3_h = 24*scale
157         drive_frame_beam_w = 56*scale
158         drive_frame_beam_h = 485*scale
159         drive_frame_connector_w = 72*scale

```

```

151 drive_frame_connector_h = 73*scale
152 drive_frame_serpent_beam_w = 171*scale
153 drive_frame_serpent_connector_x = drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + drive_frame_serpent_beam_w -
    ↳ drive_serpentine_connector2_h
154 drive_frame_base_w = 309*scale
155 drive_frame_base_h = 41*scale
156 sense_comb_finger_dist = (small_gap + large_gap + sense_comb_finger_h)
157 proof_mass_fingers_pole_w = 15*scale
158 proof_mass_fingers_pole_h = (3*(sense_comb_finger_dist+sense_comb_finger_h))
159 sense_comb_finger_w = 243*scale
160 sense_comb_finger_num = 3
161 drive_comb_finger_w = 48*scale
162 drive_comb_finger_h = 9*scale
163 drive_comb_finger_dist = (small_gap + large_gap + drive_comb_finger_h)
164 drive_comb_finger_num = 8
165 mirror_quarter = drive_serpentine_beam2_x + serpentine_width +
    ↳ drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + proof_mass_w
166 mirror_gyro = mirror_quarter*2 - drive_anchor_width/2
167 drive_coupling_beam_w = 118.5*scale
168 drive_coupling_beam_h = 21*scale
169 drive_coupling_dist = 42.75*scale
170 drive_coupling_beam_vert_w = 9*scale
171 drive_coupling_dist2 = 95*scale
172 drive_coupling_beam_vert_h = drive_coupling_dist2*2 + drive_coupling_beam_h
173 drive_coupling_connector_w = 15*scale
174 drive_coupling_connector_h = 12*scale
175
176 Volume = ((drive_anchor_height*drive_anchor_width)*4 + (
    ↳ drive_serpentine_connector_h*drive_serpentine_connector_w)*4
177 + (serpentine_width*drive_serpentine_beam_h)*8 + (
    ↳ drive_serpentine_connector2_h*drive_serpentine_connector2_w)*8 +
178 (drive_serpentine_connector3_h*drive_serpentine_connector3_w)*4 + (
    ↳ drive_frame_beam_w*drive_frame_beam_h)*4 +
179 (drive_frame_connector_h*drive_frame_connector_w)*4 + (
    ↳ drive_frame_serpent_beam_w*serpentine_width)*8 +
180 (drive_frame_base_w*drive_frame_base_h)*4 + (proof_mass_beam_w*
    ↳ proof_mass_beam_h)*4 +
181 (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
    ↳ proof_mass_fingers_pole_h)*4 +
182 (sense_comb_finger_h*sense_comb_finger_w)*12 + (drive_comb_finger_h*
    ↳ drive_comb_finger_w)*32)*thickness
183

```

```

184 Volume_proof_mass = ((proof_mass_beam_w*proof_mass_beam_h)*4 +
185 (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
    ↳ proof_mass_fingers_pole_h)*4 +
186 (sense_comb_finger_h*sense_comb_finger_w)*12)*thickness
187
188 Volume_drive_frame = ((drive_frame_beam_w*drive_frame_beam_h)*4 + (
    ↳ drive_frame_connector_w*drive_frame_connector_h)*4 +
189 (drive_frame_serpent_beam_w*serpentine_width)*8 + (
    ↳ drive_serpentine_connector2_w*drive_serpentine_connector2_h)*4 +
190 (drive_frame_base_h*drive_frame_base_w)*4)*thickness
191
192 Volume_drive = Volume_proof_mass + Volume_drive_frame
193 # Strain operator
194 def eps(v):
195     return sym(grad(v))
196
197 # Stress tensor
198 def sigma(v):
199     return lmbda*tr(eps(v))*Identity(3) + 2.0*mu*eps(v)
200
201 # Function Space
202 V = VectorFunctionSpace(mesh,'Lagrange',degree=3)
203 u_ = TrialFunction(V)
204 du = TestFunction(V)
205
206
207 # Boundary Conditions
208 # Upper Left Quarter
209
210 def drive_anchor_left(x,on_boundary):
211     return near(x[0],0.)
212
213 def drive_anchor_left2(x,on_boundary):
214     return near(x[0],drive_anchor_width)
215
216 def drive_anchor_left3(x,on_boundary):
217     return near(x[1],0.) and x[0] >= 0 and x[0] <= drive_anchor_width
218
219 def drive_anchor_left4(x,on_boundary):
220     return near(x[1],drive_anchor_height) and x[0] >= 0 and x[0] <=
    ↳ drive_anchor_width
221
222 def drive_anchor_left5(x,on_boundary):
223     return near(x[1],mirror_half_helper(drive_frame_beam_h,0)) and x[0] >= 0
    ↳ and x[0] <= drive_anchor_width

```

```

224
225 def drive_anchor_left6(x,on_boundary):
226     return near(x[1],mirror_half_helper(drive_frame_beam_h,0)-
        ↪ drive_anchor_height) and x[0] >= 0 and x[0] <= drive_anchor_width
227
228 def drive_middle_anchor(x,on_boundary):
229     return near(x[0],mirror_quarter_helper(mirror_quarter,0)) and x[1] >= 0
        ↪ and x[1] <= drive_anchor_height
230
231 def drive_middle_anchor2(x,on_boundary):
232     return near(x[0],mirror_quarter_helper(mirror_quarter,0)-
        ↪ drive_anchor_width) and x[1] >= 0 and x[1] <= drive_anchor_height
233
234 def drive_middle_anchor12(x,on_boundary):
235     return near(x[0],mirror_quarter_helper(mirror_quarter,0)) and x[1] >=
        ↪ mirror_half_helper(drive_frame_beam_h,0)-drive_anchor_height and x
        ↪ [1] <= mirror_half_helper(drive_frame_beam_h,0)
236
237 def drive_middle_anchor22(x,on_boundary):
238     return near(x[0],mirror_quarter_helper(mirror_quarter,0)-
        ↪ drive_anchor_width) and x[1] >= mirror_half_helper(
        ↪ drive_frame_beam_h,0)-drive_anchor_height and x[1] <=
        ↪ mirror_half_helper(drive_frame_beam_h,0)
239
240 def drive_middle_anchor3(x,on_boundary):
241     return near(x[1],0.) and x[0] >= mirror_quarter_helper(mirror_quarter,0)-
        ↪ drive_anchor_width and x[0] <= mirror_quarter_helper(
        ↪ mirror_quarter,0)
242
243 def drive_middle_anchor4(x,on_boundary):
244     return near(x[1],drive_anchor_height) and x[0] >= mirror_quarter_helper(
        ↪ mirror_quarter,0)-drive_anchor_width and x[0] <=
        ↪ mirror_quarter_helper(mirror_quarter,0)
245
246 def drive_middle_anchor5(x,on_boundary):
247     return near(x[1],mirror_half_helper(drive_frame_beam_h,0)) and x[0] >=
        ↪ mirror_quarter_helper(mirror_quarter,0)-drive_anchor_width and x
        ↪ [0] <= mirror_quarter_helper(mirror_quarter,0)
248
249 def drive_middle_anchor6(x,on_boundary):
250     return near(x[1],mirror_half_helper(drive_frame_beam_h,0)-
        ↪ drive_anchor_height) and x[0] >= mirror_quarter_helper(
        ↪ mirror_quarter,0)-drive_anchor_width and x[0] <=
        ↪ mirror_quarter_helper(mirror_quarter,0)
251

```

```

252 bc = [DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left),
253        DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left2),
254        DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left3),
255        DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left4),
256        DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left5),
257        DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left6),
258        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor),
259        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor2),
260        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor12),
261        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor22),
262        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor3),
263        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor4),
264        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor5),
265        DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor6)]
266
267 # Change the force to x and y, depending on whether the desired displacement
    ↪ is from actuation force or coriolis force (a change in the volume is
    ↪ also need)
268 f = Constant((0.,force/Volume_proof_mass,0.))
269 T = Constant((0,0,0))
270 V = VectorFunctionSpace(mesh,'Lagrange',degree=3)
271 du = TrialFunction(V)
272 u_ = TestFunction(V)
273 a = inner(sigma(du),eps(u_))*dx
274 l = dot(f,u_)*dx
275
276 u = Function(V, name='Displacement')
277 solve(a == l, u, bc)
278 disp = u(mirror_quarter,mirror_half_helper,thickness/2)
279
280 # Set up file for exporting results
281 file_results = XDMFFile("gyro_displacement.xdmf")
282 file_results.parameters["flush_output"] = True
283 file_results.parameters["functions_share_mesh"] = True
284 file_results.write(u,0)
285
286 return disp[1]

```

Listing II.3: Modal analysis simulation script

```

1 # MEMS Gyroscope modal analysis script
2 # @ruiesteves
3
4 # Imports
5 from fenics import *
6 import numpy as np

```



---

```

7  import time
8  import math
9
10
11  # Definitions
12
13
14  # For PolySi
15  E = Constant(170e9)
16  nu = Constant(0.28)
17  rho = 2329
18  mu = E/2/(1+nu)
19  lmbda = E*nu/(1+nu)/(1-2*nu)
20
21
22  # Meshing
23  mesh = Mesh("gyroscope.xml")
24
25
26  # Helper functions
27  def mirror_quarter_helper(mirror_quarter,x_point):
28      dist = mirror_quarter - x_point
29      x_new = mirror_quarter + dist
30      return x_new
31
32  def mirror_half_helper(drive_frame_beam_h,y_point):
33      dist = drive_frame_beam_h - y_point
34      y_new = drive_frame_beam_h + dist
35      return y_new
36
37
38
39
40
41  def main(serpentine_width,proof_mass_beam_w,proof_mass_beam_h,
42  proof_mass_w,proof_mass_h,sense_comb_finger_h):
43
44      scale = 1e-6
45      cl = 80*scale
46      small_cl = 9*scale
47      thickness = 50*scale
48      small_gap = 3*scale
49      large_gap = 4*small_gap
50      drive_anchor_width = 124*scale
51      drive_anchor_height = 126*scale

```

```
52 drive_serpentine_connector_w = 21*scale
53 drive_serpentine_connector_h = 24*scale
54 drive_serpentine_beam_h = 194*scale
55 drive_serpentine_connector2_w = 17*scale
56 drive_serpentine_connector2_h = 21*scale
57 drive_serpentine_beam2_x = drive_anchor_width + drive_serpentine_connector_w
    ↳ + serpentine_width + drive_serpentine_connector2_w
58 drive_serpentine_connector3_w = 17*scale
59 drive_serpentine_connector3_h = 24*scale
60 drive_frame_beam_w = 56*scale
61 drive_frame_beam_h = 485*scale
62 drive_frame_connector_w = 72*scale
63 drive_frame_connector_h = 73*scale
64 drive_frame_serpent_beam_w = 171*scale
65 drive_frame_serpent_connector_x = drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + drive_frame_serpent_beam_w -
    ↳ drive_serpentine_connector2_h
66 drive_frame_base_w = 309*scale
67 drive_frame_base_h = 41*scale
68 sense_comb_finger_dist = (small_gap + large_gap + sense_comb_finger_h)
69 proof_mass_fingers_pole_w = 15*scale
70 proof_mass_fingers_pole_h = (3*(sense_comb_finger_dist+sense_comb_finger_h))
71 sense_comb_finger_w = 243*scale
72 sense_comb_finger_num = 3
73 drive_comb_finger_w = 48*scale
74 drive_comb_finger_h = 9*scale
75 drive_comb_finger_dist = (small_gap + large_gap + drive_comb_finger_h)
76 drive_comb_finger_num = 8
77 mirror_quarter = drive_serpentine_beam2_x + serpentine_width +
    ↳ drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + proof_mass_w
78 mirror_gyro = mirror_quarter*2 - drive_anchor_width/2
79 drive_coupling_beam_w = 118.5*scale
80 drive_coupling_beam_h = 21*scale
81 drive_coupling_dist = 42.75*scale
82 drive_coupling_beam_vert_w = 9*scale
83 drive_coupling_dist2 = 95*scale
84 drive_coupling_beam_vert_h = drive_coupling_dist2*2 + drive_coupling_beam_h
85 drive_coupling_connector_w = 15*scale
86 drive_coupling_connector_h = 12*scale
87
88 # Functions
89 def eps(v):
90     #return 0.5*(nabla_grad(v) + nabla_grad(v).T)
```

---

```

91     return sym(grad(v))
92
93 def sigma(v):
94     return lmbda*tr(eps(v))*Identity(3) + 2.0*mu*eps(v)
95
96 # Function Space
97 V = VectorFunctionSpace(mesh, 'Lagrange', degree=3)
98 u_ = TrialFunction(V)
99 du = TestFunction(V)
100
101 # Boundary Conditions
102 # Upper Left Quarter
103
104 def drive_anchor_left(x, on_boundary):
105     return near(x[0], 0.)
106
107 def drive_anchor_left2(x, on_boundary):
108     return near(x[0], drive_anchor_width)
109
110 def drive_anchor_left3(x, on_boundary):
111     return near(x[1], 0.) and x[0] >= 0 and x[0] <= drive_anchor_width
112
113 def drive_anchor_left4(x, on_boundary):
114     return near(x[1], drive_anchor_height) and x[0] >= 0 and x[0] <=
        ↪ drive_anchor_width
115
116 def drive_anchor_left5(x, on_boundary):
117     return near(x[1], mirror_half_helper(drive_frame_beam_h, 0)) and x[0] >= 0
        ↪ and x[0] <= drive_anchor_width
118
119 def drive_anchor_left6(x, on_boundary):
120     return near(x[1], mirror_half_helper(drive_frame_beam_h, 0)-
        ↪ drive_anchor_height) and x[0] >= 0 and x[0] <= drive_anchor_width
121
122 def drive_middle_anchor(x, on_boundary):
123     return near(x[0], mirror_quarter_helper(mirror_quarter, 0)) and x[1] >= 0
        ↪ and x[1] <= drive_anchor_height
124
125 def drive_middle_anchor2(x, on_boundary):
126     return near(x[0], mirror_quarter_helper(mirror_quarter, 0)-
        ↪ drive_anchor_width) and x[1] >= 0 and x[1] <= drive_anchor_height
127
128 def drive_middle_anchor12(x, on_boundary):

```

```

129     return near(x[0],mirror_quarter_helper(mirror_quarter,0)) and x[1] >=
        ↪ mirror_half_helper(drive_frame_beam_h,0)-drive_anchor_height and x
        ↪ [1] <= mirror_half_helper(drive_frame_beam_h,0)
130
131 def drive_middle_anchor22(x,on_boundary):
132     return near(x[0],mirror_quarter_helper(mirror_quarter,0)-
        ↪ drive_anchor_width) and x[1] >= mirror_half_helper(
        ↪ drive_frame_beam_h,0)-drive_anchor_height and x[1] <=
        ↪ mirror_half_helper(drive_frame_beam_h,0)
133
134 def drive_middle_anchor3(x,on_boundary):
135     return near(x[1],0.) and x[0] >= mirror_quarter_helper(mirror_quarter,0)-
        ↪ drive_anchor_width and x[0] <= mirror_quarter_helper(
        ↪ mirror_quarter,0)
136
137 def drive_middle_anchor4(x,on_boundary):
138     return near(x[1],drive_anchor_height) and x[0] >= mirror_quarter_helper(
        ↪ mirror_quarter,0)-drive_anchor_width and x[0] <=
        ↪ mirror_quarter_helper(mirror_quarter,0)
139
140 def drive_middle_anchor5(x,on_boundary):
141     return near(x[1],mirror_half_helper(drive_frame_beam_h,0)) and x[0] >=
        ↪ mirror_quarter_helper(mirror_quarter,0)-drive_anchor_width and x
        ↪ [0] <= mirror_quarter_helper(mirror_quarter,0)
142
143 def drive_middle_anchor6(x,on_boundary):
144     return near(x[1],mirror_half_helper(drive_frame_beam_h,0)-
        ↪ drive_anchor_height) and x[0] >= mirror_quarter_helper(
        ↪ mirror_quarter,0)-drive_anchor_width and x[0] <=
        ↪ mirror_quarter_helper(mirror_quarter,0)
145
146
147
148
149
150 bc = [DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left),
151       DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left2),
152       DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left3),
153       DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left4),
154       DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left5),
155       DirichletBC(V, Constant((0.,0.,0.)),drive_anchor_left6),
156       DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor),
157       DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor2),
158       DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor12),
159       DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor22),

```

---

```

160         DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor3),
161         DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor4),
162         DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor5),
163         DirichletBC(V, Constant((0.,0.,0.)),drive_middle_anchor6)]
164
165
166     # Matrices
167     k_form = inner(sigma(du),eps(u_))*dx
168     l_form = Constant(1.)*u_[0]*dx
169     K = PETScMatrix()
170     b = PETScVector()
171     assemble_system(k_form,l_form,bc,A_tensor=K,b_tensor=b)
172
173     m_form = rho*dot(du,u_)*dx
174     M = PETScMatrix()
175     assemble(m_form, tensor=M)
176
177     # Eigenvalues/Eigensolver
178     eigensolver = SLEPcEigenSolver(K,M)
179     eigensolver.parameters['problem_type'] = 'gen_hermitian'
180     #eigensolver.parameters['spectrum'] = 'smallest real'
181     eigensolver.parameters['spectral_transform'] = 'shift-and-invert'
182     eigensolver.parameters['spectral_shift'] = 0.
183     #PETScOptions.set("st_pc_factor_mat_solver_type", "mumps")
184     N_eig = 6
185     eigensolver.solve(N_eig)
186     #print (eigensolver.parameters.str(True))
187
188     # Export results
189     file_results = XDMFFile('gyro_modal_analysis.xdmf')
190     file_results.parameters['flush_output'] = True
191     file_results.parameters['functions_share_mesh'] = True
192
193     r1,c1,rx1,cx1 = eigensolver.get_eigenpair(0)
194     r3,c3,rx3,cx3 = eigensolver.get_eigenpair(3)
195     u = Function(V)
196     u.vector()[:] = rx1
197     file_results.write(u,0)
198
199     # Extraction
200     for i in range(N_eig):
201         r,c,rx,cx = eigensolver.get_eigenpair(i)
202         freq = sqrt(r)/2/pi
203         print('Mode:',i,'_mode_', 'Freq:',freq,'[Hz]')
204

```

```

205     freq_final_drive = sqrt(r1)/2/pi
206     freq_final_sense = sqrt(r3)/2/pi
207
208     return freq_final_drive, freq_final_sense

```

Listing II.4: Damping calculation script

```

1  # MEMS Gyroscope squeeze and slide film damping calculation script
2  # @ruiesteves
3
4  # Imports
5  import gyro_modal
6  import math
7
8  # Constants
9  scale = 1e-6
10 L = 18*scale
11 small_gap = 3*scale
12 mu = 1.86e-5
13 lamb = 0.067e-6
14 thickness = 50*scale
15 drive_comb_finger_num = 8
16
17 # Slide damping calculation
18 def damping_drive():
19     Kn = lamb/small_gap
20     mu_eff = mu/(1 + 2*Kn + (0.2*Kn**0.788)*math.exp(-Kn/10))
21     A = L*thickness
22     c_drive = 4 * drive_comb_finger_num * mu_eff * (A/small_gap)
23     return c_drive
24
25 def q_factor_drive(serpentine_width,proof_mass_beam_w,proof_mass_beam_h,
26     ↪ proof_mass_w,proof_mass_h,sense_comb_finger_h,drive_frequency):
27     # Constants
28     scale = 1e-6
29     cl = 80*scale
30     small_cl = 9*scale
31     thickness = 50*scale
32     small_gap = 3*scale
33     large_gap = 4*small_gap
34     drive_anchor_width = 124*scale
35     drive_anchor_height = 126*scale
36     drive_serpentine_connector_w = 21*scale
37     drive_serpentine_connector_h = 24*scale
38     drive_serpentine_beam_h = 194*scale
39     drive_serpentine_connector2_w = 17*scale

```

```

39 drive_serpentine_connector2_h = 21*scale
40 drive_serpentine_beam2_x = drive_anchor_width + drive_serpentine_connector_w
    ↳ + serpentine_width + drive_serpentine_connector2_w
41 drive_serpentine_connector3_w = 17*scale
42 drive_serpentine_connector3_h = 24*scale
43 drive_frame_beam_w = 56*scale
44 drive_frame_beam_h = 485*scale
45 drive_frame_connector_w = 72*scale
46 drive_frame_connector_h = 73*scale
47 drive_frame_serpent_beam_w = 171*scale
48 drive_frame_serpent_connector_x = drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + drive_frame_serpent_beam_w -
    ↳ drive_serpentine_connector2_h
49 drive_frame_base_w = 309*scale
50 drive_frame_base_h = 41*scale
51 sense_comb_finger_dist = (small_gap + large_gap + sense_comb_finger_h)
52 proof_mass_fingers_pole_w = 15*scale
53 proof_mass_fingers_pole_h = (3*(sense_comb_finger_dist+sense_comb_finger_h))
54 sense_comb_finger_w = 243*scale
55 sense_comb_finger_num = 3
56 drive_comb_finger_w = 48*scale
57 drive_comb_finger_h = 9*scale
58 drive_comb_finger_dist = (small_gap + large_gap + drive_comb_finger_h)
59 drive_comb_finger_num = 8
60 mirror_quarter = drive_serpentine_beam2_x + serpentine_width +
    ↳ drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + proof_mass_w
61 mirror_gyro = mirror_quarter*2 - drive_anchor_width/2
62 drive_coupling_beam_w = 118.5*scale
63 drive_coupling_beam_h = 21*scale
64 drive_coupling_dist = 42.75*scale
65 drive_coupling_beam_vert_w = 9*scale
66 drive_coupling_dist2 = 95*scale
67 drive_coupling_beam_vert_h = drive_coupling_dist2*2 + drive_coupling_beam_h
68 drive_coupling_connector_w = 15*scale
69 drive_coupling_connector_h = 12*scale
70
71 Volume = ((drive_anchor_height*drive_anchor_width)*4 + (
    ↳ drive_serpentine_connector_h*drive_serpentine_connector_w)*4
72 + (serpentine_width*drive_serpentine_beam_h)*8 + (
    ↳ drive_serpentine_connector2_h*drive_serpentine_connector2_w)*8 +
73 (drive_serpentine_connector3_h*drive_serpentine_connector3_w)*4 + (
    ↳ drive_frame_beam_w*drive_frame_beam_h)*4 +

```

```

74 (drive_frame_connector_h*drive_frame_connector_w)*4 + (
    ↳ drive_frame_serpent_beam_w*serpentine_width)*8 +
75 (drive_frame_base_w*drive_frame_base_h)*4 + (proof_mass_beam_w*
    ↳ proof_mass_beam_h)*4 +
76 (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
    ↳ proof_mass_fingers_pole_h)*4 +
77 (sense_comb_finger_h*sense_comb_finger_w)*12 + (drive_comb_finger_h*
    ↳ drive_comb_finger_w)*32)*thickness
78
79 Volume_proof_mass = ((proof_mass_beam_w*proof_mass_beam_h)*4 +
80 (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
    ↳ proof_mass_fingers_pole_h)*4 +
81 (sense_comb_finger_h*sense_comb_finger_w)*12)*thickness
82
83 Volume_drive_frame = ((drive_frame_beam_w*drive_frame_beam_h)*4 + (
    ↳ drive_frame_connector_w*drive_frame_connector_h)*4 +
84 (drive_frame_serpent_beam_w*serpentine_width)*8 + (
    ↳ drive_serpentine_connector2_w*drive_serpentine_connector2_h)*4 +
85 (drive_frame_base_h*drive_frame_base_w)*4)*thickness
86
87 Volume_drive = Volume_proof_mass + Volume_drive_frame
88
89 drive_mass = Volume_drive*rho
90 c_drive = damping_drive()
91 q_factor = drive_mass * (drive_frequency*2*math.pi) / c_drive
92 return q_factor
93
94 # Squeeze film damping calculation
95 def damping_sense():
96     Kn = lamb/small_gap
97     mu_eff = mu/(1+9.638*Kn**1.159)
98     Pa = 101.3e3
99     A = L_sense*thickness
100    c = L_sense/thickness
101    squeeze_number = (12*mu_eff*10*2*math.pi*L_sense**2)/(Pa*small_gap**2)
102    sum = 0
103    for m in range(1,10,2):
104        for n in (1,10,2):
105            sum = sum + (m**2 + c**2 * n**2)/((m*n)**2 * ((m**2 + c**2 * n**2)**2
                ↳ + (squeeze_number**2 / math.pi**4)))
106
107    F_damping = ((64*squeeze_number*Pa*A)/(math.pi**6 * small_gap)) * sum
108    c_sense = F_damping * sense_comb_finger_num * 4
109    return c_sense
110

```



---

```

111 def q_factor_sense(serpentine_width,proof_mass_beam_w,proof_mass_beam_h,
    ↳ proof_mass_w,proof_mass_h,sense_comb_finger_h,sense_frequency):
112     # Constants
113     scale = 1e-6
114     cl = 80*scale
115     small_cl = 9*scale
116     thickness = 50*scale
117     small_gap = 3*scale
118     large_gap = 4*small_gap
119     drive_anchor_width = 124*scale
120     drive_anchor_height = 126*scale
121     drive_serpentine_connector_w = 21*scale
122     drive_serpentine_connector_h = 24*scale
123     drive_serpentine_beam_h = 194*scale
124     drive_serpentine_connector2_w = 17*scale
125     drive_serpentine_connector2_h = 21*scale
126     drive_serpentine_beam2_x = drive_anchor_width + drive_serpentine_connector_w
    ↳ + serpentine_width + drive_serpentine_connector2_w
127     drive_serpentine_connector3_w = 17*scale
128     drive_serpentine_connector3_h = 24*scale
129     drive_frame_beam_w = 56*scale
130     drive_frame_beam_h = 485*scale
131     drive_frame_connector_w = 72*scale
132     drive_frame_connector_h = 73*scale
133     drive_frame_serpent_beam_w = 171*scale
134     drive_frame_serpent_connector_x = drive_serpentine_beam2_x +
    ↳ serpentine_width + drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + drive_frame_serpent_beam_w -
    ↳ drive_serpentine_connector2_h
135     drive_frame_base_w = 309*scale
136     drive_frame_base_h = 41*scale
137     sense_comb_finger_dist = (small_gap + large_gap + sense_comb_finger_h)
138     proof_mass_fingers_pole_w = 15*scale
139     proof_mass_fingers_pole_h = (3*(sense_comb_finger_dist+sense_comb_finger_h))
140     sense_comb_finger_w = 243*scale
141     sense_comb_finger_num = 3
142     drive_comb_finger_w = 48*scale
143     drive_comb_finger_h = 9*scale
144     drive_comb_finger_dist = (small_gap + large_gap + drive_comb_finger_h)
145     drive_comb_finger_num = 8
146     mirror_quarter = drive_serpentine_beam2_x + serpentine_width +
    ↳ drive_serpentine_connector3_w+drive_frame_beam_w +
    ↳ drive_frame_connector_w + proof_mass_w
147     mirror_gyro = mirror_quarter*2 - drive_anchor_width/2
148     drive_coupling_beam_w = 118.5*scale

```

```

149     drive_coupling_beam_h = 21*scale
150     drive_coupling_dist = 42.75*scale
151     drive_coupling_beam_vert_w = 9*scale
152     drive_coupling_dist2 = 95*scale
153     drive_coupling_beam_vert_h = drive_coupling_dist2*2 + drive_coupling_beam_h
154     drive_coupling_connector_w = 15*scale
155     drive_coupling_connector_h = 12*scale
156
157     Volume = ((drive_anchor_height*drive_anchor_width)*4 + (
158         ↪ drive_serpentine_connector_h*drive_serpentine_connector_w)*4
159     + (serpentine_width*drive_serpentine_beam_h)*8 + (
160         ↪ drive_serpentine_connector2_h*drive_serpentine_connector2_w)*8 +
161     (drive_serpentine_connector3_h*drive_serpentine_connector3_w)*4 + (
162         ↪ drive_frame_beam_w*drive_frame_beam_h)*4 +
163     (drive_frame_connector_h*drive_frame_connector_w)*4 + (
164         ↪ drive_frame_serpent_beam_w*serpentine_width)*8 +
165     (drive_frame_base_w*drive_frame_base_h)*4 + (proof_mass_beam_w*
166         ↪ proof_mass_beam_h)*4 +
167     (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
168         ↪ proof_mass_fingers_pole_h)*4 +
169     (sense_comb_finger_h*sense_comb_finger_w)*12 + (drive_comb_finger_h*
170         ↪ drive_comb_finger_w)*32)*thickness
171
172     Volume_proof_mass = ((proof_mass_beam_w*proof_mass_beam_h)*4 +
173     (proof_mass_w*proof_mass_h)*4 + (proof_mass_fingers_pole_w*
174         ↪ proof_mass_fingers_pole_h)*4 +
175     (sense_comb_finger_h*sense_comb_finger_w)*12)*thickness
176
177     Volume_drive_frame = ((drive_frame_beam_w*drive_frame_beam_h)*4 + (
178         ↪ drive_frame_connector_w*drive_frame_connector_h)*4 +
179     (drive_frame_serpent_beam_w*serpentine_width)*8 + (
180         ↪ drive_serpentine_connector2_w*drive_serpentine_connector2_h)*4 +
181     (drive_frame_base_h*drive_frame_base_w)*4)*thickness
182
183     Volume_drive = Volume_proof_mass + Volume_drive_frame
184
185     mass_sense = Volume_proof_mass*rho
186     c_sense = damping_sense()
187     q_factor = mass_sense * sense_frequency*2*math.pi / c_sense
188     return q_factor

```

Listing II.5: Electrical domain simulation script

```

1  # MEMS Gyroscope electrical domain simulation
2  # @ruiesteves
3

```

```

4  # Imports
5  import gyro_disp
6
7  # Constants
8  scale = 1e-6
9  thickness = 50*scale
10 sense_comb_finger_num = 3
11 small_gap = 3*scale
12 L_sense = 18*scale
13 epsilon0 = 8.85e-12
14
15 # Functions
16 def main(serpentine_width,proof_mass_beam_w,proof_mass_beam_h,proof_mass_w,
    ↪ proof_mass_h,sense_comb_finger_h,q_factor_sense,q_factor_drive,
    ↪ drive_frequency,sense_frequency):
17     disp = gyro_disp.disp_equations(serpentine_width,proof_mass_beam_w,
    ↪ proof_mass_beam_h,proof_mass_w,proof_mass_h,sense_comb_finger_h,
    ↪ q_factor_sense,q_factor_drive,drive_frequency,sense_frequency)
18
19     def cap_change(disp):
20         C = 2*sense_comb_finger_num*2 * epsilon0 * thickness * L_sense * disp / (
    ↪ small_gap**2)
21         print("Cap_change:",C*1e15,"fF")
22         return C
23
24     def c2v(cap):
25         v = 2 * cap * 2.5 * (1/100e-15)
26         print("Output_voltage:",v*1e3,"mV")
27         return v
28
29     return c2v(cap_change(disp))

```

Listing II.6: Genetic algorithm script for MEMS gyroscope

```

1  # Python Gyroscope GA
2  # @ruiesteves
3
4  # Imports
5  import gyro_geo
6  import gyro_disp
7  import gyro_elec
8  import gyro_modal
9  import gyro_damping
10 import numpy as np
11 import math as math
12 import random as rand

```

```
13 import copy
14
15 # Initial parameters of the device to be optimized
16 scale = 1e-6
17 suspension_beam_width = 20*scale
18 proof_mass_frame_width = 430*scale
19 proof_mass_frame_length = 60*scale
20 proof_mass_width = 290*scale
21 proof_mass_length = 220*scale
22 sense_comb_finger_w = 14*scale
23
24 initial = [suspension_beam_width,proof_mass_frame_width,proof_mass_frame_length,
    ↪ proof_mass_width,proof_mass_length,sense_comb_finger_w]
25
26 # Classes
27 class GA_device:
28
29     def __init__(self,id):
30         self.list_parameters = []
31         self.id = id
32
33     def calc_freq(self):
34         list = self.list_parameters
35         self.freq_drive, self.freq_sense = gyro_modal.main(list[0],list[1],list
    ↪ [2],list[3],list[4],list[5])
36
37     def calc_qfactor(self):
38         list = self.list_parameters
39         self.qfactor_drive = gyro_damping.q_factor_drive(list[0],list[1],list[2],
    ↪ list[3],list[4],list[5],self.freq_drive)
40         self.qfactor_sense = gyro_damping.q_factor_sense(list[0],list[1],list[2],
    ↪ list[3],list[4],list[5],self.freq_sense)
41
42     def calc_sensitivity(self):
43         list = self.list_parameters
44         self.sensitivity = gyro_elec.main(list[0],list[1],list[2],list[3],list[4],
    ↪ list[5],self.q_factor_drive,self.q_factor_sense,self.freq_drive,
    ↪ self.freq_sense)
45
46     def calc_fom(self):
47         list = self.list_parameters
48         try:
49             gyro_geo.build(list[0],list[1],list[2],list[3],list[4],list[5])
50             self.calc_freq()
51             self.calc_qfactor()
```

```

52         self.calc_sensitivity()
53         self.fom = (1/(self.freq_sense - self.freq_drive) * self.sensitivity *
                    ↪ self.qfactor_sense * 1e6
54     except:
55         print("Geometry_became_invalid_for_device",self.id)
56         self.fom = 0
57
58
59 class GA: # GA class, initiated with a list of devices, a list of mutation
        ↪ chances and a list of mutation relative size
60
61     def __init__(self,list_devices,mutation_chance,mutation_size):
62         self.list_devices = list_devices # Must be a list of GA_devices
63         self.mutation_chance = mutation_chance # A list, with different (or not)
        ↪ mutation chances for each parameter
64         self.mutation_size = mutation_size # Same as above, this time for
        ↪ mutation_sizes (IMPORTANT to check)
65
66     def mutate(self,dev): # The mutation function, mutating the parameters
        ↪ according to their mutation chance and size
67         le = len(dev.list_parameters)
68         for i in range(le):
69             if rand.uniform(0,1) < self.mutation_chance[i]:
70                 if rand.uniform(0,1) < 0.5:
71                     dev.list_parameters[i] = dev.list_parameters[i] + dev.
        ↪ list_parameters[i]*self.mutation_size[i]
72                 else:
73                     dev.list_parameters[i] = dev.list_parameters[i] - dev.
        ↪ list_parameters[i]*self.mutation_size[i]
74
75     def reproduce(self,top_25):
76         new_population = []
77
78         for dev in top_25: # Passing the best 25 devices to the next generation
79             new_population.append(dev)
80
81         for dev in top_25: # Copying and mutating the best 25 devices to the next
        ↪ generation
82             new_dev = copy.deepcopy(dev)
83             self.mutate(new_dev)
84             new_population.append(new_dev)
85
86         for i in range(len(self.list_devices)//2): # Randomly mutating and
        ↪ passing half of the population to the next generation
87             new_dev_r = copy.deepcopy(self.list_devices[i])

```

```
88         self.mutate(new_dev_r)
89         new_population.append(new_dev_r)
90
91     return new_population
92
93
94     def one_generation(self):
95
96         for dev in self.list_devices:
97             dev.calc_fom()
98
99         le = len(self.list_devices)
100         scores = [self.list_devices[i].fom for i in range(le)]
101         max = np.amax(scores)
102         print(scores)
103         print(max)
104
105         top_25_index = list(np.argsort(scores))[3*(le//4):le]
106         top_25 = [self.list_devices[i] for i in top_25_index][::-1]
107
108         self.list_devices = self.reproduce(top_25)
109
110
111
112 # Script
113 print("Genetic_algorithm_optimization_for_MEMS_Gyroscope")
114 num_pop = int(input("Size_of_the_population:"))
115 num_gen = int(input("Number_of_generations:"))
116
117 initial_pop = []
118 for i in range(num_pop):
119     initial_pop.append(GA_device(i))
120     for par in range(len(initial)):
121         initial_pop[i].list_parameters.append(initial[par])
122     initial_pop[i].calc_fom()
123
124 init_ga = GA(initial_pop
125     ↪ , [0.6, 0.6, 0.6, 0.6, 0.6, 0.6], [0.122, 0.014, 0.017, 0.0105, 0.01387, 0.065])
126
127 for i in range(num_gen):
128     init_ga.one_generation()
129     for dev in init_ga.list_devices:
130         print("\n", "For_Device_number", dev.id, ":")
131         print(dev.fom, "FOM")
```

---

```
132 max_score = 0
133
134
135 for dev in init_ga.list_devices:
136     if dev.fom > max_score:
137         max_score = dev.fom
138
139 print("Maximum_FOM:",max_score)
```







## PERMITTIVITY VALUES

Table III.1: Permittivity values

Permittivity	Value
$\epsilon_0$ (free space)	$8.85 \times 10^{-12}$ F/m
$\epsilon_r$ (air)	1 F/m